GTI 5G Device RF Component Research Report





GTI 5G Device RF Component

Research Report



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1 Executive Summary

How to realize "high efficiency and low power consumption" device is a technical issue which should be emphasized on throughout the 5G RF component R&D process. The power consumption should be optimized based on the deployment plan of operators and the requirements of customers. This process should involve not only RF component vendors, but also chipset vendors and device vendors.

RF FEM is one of the most popular solutions to realize 5G NR RF components, especially for the large volume of high-end devices, due to its smaller layout area, better inter-stage matching, less design inputs, shorter test process and faster time to market. So FEM is a research and development direction worthy of attention.

According to 3GPP's schedule, the first version of 5G standard R15 will be completed in the middle of 2018 and R16 is going to be completed by the end of 2019. The 5G+ technical specification will be constantly updated since 2020. It is hoped that RF components vendors could actively participate in and track 3GPP's discussion on the specifications of 5G RF components as well as establish theoretical basis for the final specifications based on the prospective simulation and test data. In order to guarantee commercial RF components in time, RF components designers and manufactures should work together with operators, chipset vendors, device vendors and test instrument vendors to make sure the system verification and the pre-commercial trial could be completed in 2018 and 2019 separately The high performance and low cost front-end RF components are expected to be provided in proper time and volume. So the RF component vendors are supposed to cooperate with the whole industrial chain to accomplish the goal of 5G's commercialization by the end of 2020.

GTI 5G Device Component Research Report is expected to help people to develop 5G devices and to promote industrial development. This report may also help people to know more about the industrial status of 5G device RF components. Meanwhile, it may also help readers interested in 5G device RF components to gain from the further thinking.

GTI

2 Introduction

4G has completely changed our lives. While, as the society becomes much more informative, people's requirements increase rapidly. Devices are supposed to have better performance and provide more qualified service. Thus more and more opportunities and changes are created for mobile communication. Compared with 4G, 5G would have higher experiencing speed, higher connection density and lower latency. Not only the connections between people and people, but also people and things, things and things would be included into 5G scope. Aiming at constructing a cross industry ecosystem and further changing people's lives, 5G sets its sights on enhanced Mobile Broad Band (eMBB), massive Machine Type Communication (mMTC) as well as Ultra Reliable and Low Latency Communication.

China Mobile plays an important role in prompting 5G to enter the commercial stage before 2020. As the leader of the IMT-2020 requirement group, China Mobile led to complete '5G Vision and Requirement' White Paper as well as the 5G requirements in NGMN and the 5G requirements and scenarios in 3GPP. Aiming for 5G's commercialization in 2020, sub-6GHz is the focus at this moment. Considering the millimeter Wave spectrum won't be used for mobile telecomon until 2019 and after that 2~3 years will be needed for spectrum allocation in China, themunicati commercialization of 5G mmWave might be 2022 or even later.

Before the commercialization in 2020, China Mobile will complete the 3-phase validation of 5G, the key technology test, the system test and the large-scale test. The key technology test and the system test has been completed by 2017. The large-scale test has started in 2018. With the purpose of specifying the direction in developing testing prototypes, China Mobile jointly released the 'GTI Sub-6GHz 5G Device Whitepaper' with GTI industrial partners in Nov. 2017 and kicked off "GTI 5G S-Module Initiative" in Jun. 2018. The white paper analyzed the key technologies as well as the hot topics and difficult problems in the implementation of 5G pre-commercial/commercial devices. Many problems are related to 5G device RF components. So the implementation of RF components has become the key link to realize the 5G devices.

Therefore, co-operating with China Mobile 5G Innovation Center, GTI Device Working Group leads to write this "GTI 5G Device RF Component Research Report" with the industrial partners. This report mainly focuses on the 5G device RF components and has been carried out in two directions respectively, the sub-6GHz RF components and the millimeter wave RF components. Combined with the consideration of integrated circuit technology, the report analyses the industrial status, key technologies, design challenges, alternative process and research progress of core 5G RF components, such as power amplifier, filter, low noise amplifier and switch. Some related 'Black Technologies' which may have great influence on future RF components are also introduced in the report.

We sincerely thank all the contributors for their hard work in writing this report.

Chapter 5 5G Device RF Component Industry Status: HiWafer, Soitec, Qorvo, Skyworks, TAIYO YUDEN, Murata, VanChip, Smarter Micro and Huntersun etc.



Chapter 6 Sub-6GHz 5G Device RF Component

6.1 Sub-6GHz 5G Power Amplifier: Skyworks, Qorvo, VanChip, HiWafer, and Smarter Micro, etc.

6.2 Sub-6GHz 5G Filter: TAIYO YUDEN, Qorvo, Skyworks and Huntersun, ect.

6.3 Sub-6GHz 5G Low Noise Amplifier: Qorvo and HiWafer, etc.

Chapter 7 mmWave 5G Device RF Component: HiWafer, Murata and Qorvo, etc.

Chapter 8 Related 'Black Technologies': Soitec, Qorvo and Skyworks, etc.

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This report will be continuously updated according to the research and development progress.



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4 Abbreviations

Abbreviation	Explanation
BAW	bulk acoustic wave
СС	Component Carrier
CMOS	Complementary Metal Oxide Semiconductor
DC	Dual Connectivity
eMBB	Enhanced Mobile Broadband
ESD	Electro-Static discharge
FBB	Forward Back Gate bias
FBAR	Film Bulk Acoustic Resonator
FD	Fully Depleted
gNB	NR node
HEMT	High Electron Mobility Transistor
HSP	Harmonic Suppression Process
HPUE	High Power UE
IPD	Integrated Product Development
LTCC	Low Temperature Co-fired Ceramic
MEMS	Micro-Electro-Mechanical System
МІМО	Multiple-Input Multiple-Output
mMTC	Massive Machine Type Communication
mmWave	millimeter Wave
МММВ	Multimode Multiband
MMIC	Monolithic Microwave Integrated Circuit
MOSFET	Metal–Oxide–Semiconductor Field-Effect Transistor
MU-MIMO	Multi-User MIMO
NSA	Non-Standalone
OFDM	Orthogonal Frequency Division Multiplexing
pHEMT	Pseudomorphic HEMT
РРАС	Performance, Power, Area, and Cost
PAE	Power Added Efficiency
PD	Partially Depleted
RFeSI	RF enhanced Signal Integrity
RFFE	Radio Frequency Front-end



SAW	surface acoustic wave
SA	Standalone
SOI	Silicon on Insulator
SIMOX	Separation by Implantation of Oxygen
SU-MIMO	Single-User MIMO
UE	User Equipment
URLLC	Ultra-Reliable and Low Latency Communications
UTBB	Ultra Thin Body and Box
3GPP	The 3rd Generation Partnership Project

5 5G Device RF Component Industry Status

Based on the Navian predication, the total market size of RF front-end modules for mobile communications devices will grow from \$ 9.2 billion in 2014 to \$ 17 billion in 2019.





At present, the RF front-end chip market is mainly divided into two categories: a class of acoustic technology-based filters to surface acoustic wave filter (SAW) and Bulk acoustic wave (BAW) as the representative, one is the use of semiconductor technology Manufactured circuit chip, with power amplifier (PA) and switch circuit (Switch) as the representative.

The traditional SAW filter market has become saturated, with Murata, TDK and Taiyo Yuden accounting for more than 80% of the global market. Murata Manufacturing Co., Ltd. (Kabushiki-gaisha Murata Seisakusho) is a famous Japanese manufacturer of passive electronic components, such as capacitors and inductors, which is founded in 1940s. Ever since the beginning of the era of communications, Murata started business in RF aspects as well. After expanding the product lineup of filters, Murata achieved acquisition of Renesas Electronics and Peregrine Semiconductor, which leads to an integration of the lineup of RFFE products. Nowadays the product lineup of wireless communications department of Murata has almost covered all of the RFFE products including SAW and Multi-layer filters, RF switches, modules of either transceiver-end or receiver-end, power amplifiers, and RF connectors, etc. TAIYO YUDEN, after acquired Fujitsu Media Devices Ltd. in Y2010, has extended its technology portfolio by adding SAW and FBAR technologies in addition to LTCC RF device technology. Now the company is providing various RF devices (Filter, Duplexer, Diplexer, Low Pass Filter, etc.) for 2G/3G and 4G. While the company has already been working on the development of the series of Sub-6GHz filters for 5G since very early stages, it has also completed the initial technology validation to cover up to mmW ranges including both 28 GHz and 39 GHz frequency ranges in the light of upcoming 5G requirement which is being standardized within 3GPP group at this time. These three core technologies, SAW/FBAR/LTCC RF technologies, are indispensable for the implementation of upcoming 5G standard and the company will continue to enhance these technologies and develop new products through integrating three technologies. The current BAW core technologies are mainly in the hands of Broadcom (Avago) and Qorvo, as shown in figure 5-2. According to HIS data, Broadcom (Avago) and Qorvo have almost split their market share.



Figure 5-2 HIS Statistics on BAW Market Share (Up to 2014)

As shown in figure 5-3, based on Navian's 2017 statistics, the device power amplifier market, forms the oligarchical competition between Skyworks, Qorvo and Broadcom (Avago), which together accounted for 90% of the market share. Founded in 1962, Skyworks is an industryleading RF front-end semiconductor solution provider that designs and manufactures radio frequency (RF) for mobile handsets, cellular network equipment, automotive, energy management, industrial and medical applications And complete semiconductor system solutions, products include amplifiers, filters, switches, attenuators, diodes, directional couplers, front-end modules. Qorvo is the new merger of RF Micro Devices and TriQuint Semiconductor, two of the industry's leading RF solutions companies. The combined Qorvo has two key product lines: the Mobile Device Product Line, the Base Station and the Military Device Product Line, both of which Line for different markets, but also in complementary areas of advanced technology research and development. Broadcom, a maker of acquisition chips for Avago Technologies, has been renamed Broadcom Limited to focus on III-V compound semiconductor design and process technology, providing a broad range of analog, mixed-signal and optoelectronic components product and system design and development. At present, major product lines include Wireless communications, cable infrastructure, enterprise storage, industrial and others.



Skyworks Qorvo Broadcom Muruta Others

Figure 5-3 Navian Statistics for the Device Power Amplifier Market (2017)

RF-device market is almost dominated by the International RF-device companies. As the developments of 4G and 5G communication networks, the domestic RF-device companies get more opportunities. Vanchip, a company running the IC design, measurement and sale business, has lots of products used in 2G/3G communications. Lansus developed domestic PA and RF switch in 2010. Its NZ5081 PA has been used in Yulong Coopad 8180 TD-SCDMA, which is the first PA used in domestic smart phone. The customer of Lansus includes Mi, Coolpad, ZTE and MEIZU. Hunstersun, a domestic 2G/3G/4G RF front end IC supplier, 600 millions sales in 2015. Products involved 3-mode-8-frequency, 5-mode-17-frequency, 2G CMOS and 3G CMOS TxM RF front end ICs. SmarterMicro, a domestic 4G/5G RF front end fabless IC supplier, has developed the world first reconfigurable RF front end platform, called AgiPAM®. This platform utilize the flexibility of the software and high performance hard ware for the RF front end design, which can make the RF front end more intelligent and have higher performance and lower cost. This technology is very suitable for the 4G and 5G wireless system. Based on this platform, SmarterMicro has developed a series of products, which have been shipped to many countries and regions around the world. At the 25th GTI workshop, SmarterMicro demonstrated the first 5G reconfigurable L-PAMiF module, which supports ultra-high band of n77/79, and also supports HPUE and all full SRS hopping of 5G features. So, the domestic RF IC companies have strong ability of product developing.

RFIC manufacturing industry is accelerating while the RFIC design houses are blooming. In the sub-6GHz band of 5G, HiWafer has developed 2um GaAs HBT process. As the mainstream technology, this process realized the monolithic integrations of the active and passive devices, which can provide better linearity, stability and reliability, This process also fits for the 3G/4G cellphone, Wifi/WiMAX, used as power amplifiers. The high frequency bands of 5G communications are near the 30 GHz, 40 GHz, 70 GHz and 80 GHz, which is a hard work for industry. HiWafer developed 0.15 um GaAs pHEMT/ED HEMT process for high frequency bands of 5G. This process will support 20-60 GHz, which can be used for the high-speed data transmission in small base station, user end, IOT. With the advantages of high breakdown voltage, high electron saturation velocity and channel carrier mobility, low cost, the InP HBT and GaAs mHEMT process will get more attention.

Manufacturing process is developing to adapt to the demand .In sub-6GHz band, GaAs HBT is the main technology .In the mmWave, that has not come to an agreement between pHEMT, CMOS or else. HBT process technology of HiWafer is aimed at sub-6GHz market and pHEMT process is aimed at 5G high-frequency bands market.

Consumers usually prefer the devices having advantages of lower price, higher efficiency, better performance and lower power consumption etc. The SOI technology provides possibilities for devices to realize those characteristics. Besides, SOI technology can shorten time to market and require small design modification with low cost. With the advantages mentioned above, SOI technology has attracted more and more attentions in semiconductor industry.

As a semiconductor materials vendor, Soitec designs and manufactures engineered substrates that are then patterned and cut into chips to make circuits for electronic components. In meeting the technical and economic challenges of mainstream electronics, SOI is helping to speed up the mobile and digital revolutions as below:

- FD-SOI and PD-SOI: for Processors & connectivity SoCs up to mmWave;
- RF-SOI and POI: for RF Front-end Modules;
- Photonics-SOI: for Optical Transceivers;
- Power-SOI: for Smart Power ICs;
- Imager-SOI: for Imagers

In Front End Module, substrate is the foundation of each key device. In the following report, silicon (RF-SOI, PD-SOI, FD-SOI) and non silicon (POI, InPOGaAs, etc...) engineering substrate technologies to address 5G challenges are presented.

6 Sub-6GHz 5G Device RF Component

6.1 Sub-6GHz 5G Power Amplifier

Frequency and power is the basic requirement in PA design, also Linearity, along with efficiency and bandwidth, belongs to the fundamental specification of PA design in communication systems. In a sense, efficiency and linearity are contradictory, higher efficiency may lead to worse linearity. These two parties need to be balanced during PA design.

6.1.1 Existing Mobile Device Commercial Power Amplifier

6.1.1.1 Common Mobile Device RF Front-end Architecture

In commercial UE nowadays, PA needs to support 2G/3G/4G. Based on platform requirements, there are difference between 2G linear PA and 2G saturated PA (GSM saturated, EDGE linear) respectively.

In terms of RFFE architecture, usually we can see four mainstream architectures: MMMB PA+ASM architecture, MMPA + TxFEM architecture, PAMiD architecture and MMMB/2G PA + FEMiD architecture.

As shown in figure 6-1, this is block diagram of a commercial MMMB PA. The MMMB PA integrates 2G/3G/4G PA, connect with the antenna switch module ASM through external filters and duplexers.



Figure 6-1 Block diagram of a commercial MMMB PA



MMPA+ TxFEM is the most common RF front end architecture especially in the China market. As shown in figure 6-2, MMPA only integrates 3G/4G PA. 2G PA is integrated with ASM, which is called "TxFEM".



Figure 6-2 Block diagram of a commercial MMPA and TxFEM

Among these topologies, the flagship models that support most of worldwide frequency bands mainly adopt the PAMiD architecture. As shown in figure 6-3, it is a block diagram of a commercial low band PAMiD, integrates all RF and analog content between the transceiver and antenna, reduce complexity, size and time-to-market for customers with demanding architectures for advanced mobile applications.



Figure 6-3 Block diagram of a commercial LB PAMiD

PS: all the figures above are provided by Skyworks



For the PAMiD architecture, both PA and filter technologies are needed for the supplier. These requirements resist many new suppliers to enter the market. The MMMB/2G PA+FEMiD architecture, which can separate the requirements of PA and filter, draws a lot of attention of RF front end suppliers.



Figure 6-4 Block diagram of MMMB/2G PA+FEMiD

PS: figure 6-4 is provided by SmarterMicro

6.1.1.2 Key Parameters

1) Pout and Gain

The output power required by different systems is not the same. In the LTE UE, there are also different power classes like PC2 (antenna port 26dBm), PC3 (antenna port 23dBm). In order to obtain the output power of this range, the gain of the amplifier is about 20-30dB according to the level of the input signal.

2) Efficiency and PAE

PA converts the DC power from power supply to AC signal power, during the conversion, part of the DC power is converted to useful signal, and the rest is consumed by the PA itself and the parasitic components in the circuit. If use PL to represent the power on the load, PD represents the DC power provided by the power supply; then the efficiency of the PA can be simply defined as PL/PD. But this does not fully reflect the amplification function of PA. Therefore, PAE is introduced to fully reflect the relationship between PA output power and power supply, which is (PL-Pin) /PD.

3) Linearity

The nonlinear distortion produced by PA is reflected on both amplitude and phase. Generally, we evaluate the spectrum expansion by measuring the response of PA to the modulation signal, for example, the Adjacent Channel Leakage Ratio (ACLR).

Due to nonlinear distortion, both amplitude and phase of signal will be distorted at the same

time. Therefore, we use the error between the point of the actual signal and the point of the ideal signal to represent the linearity index, which is the Error Vector Magnitude (EVM).

6.1.1.3 Influence Factors

1) Bandwidth and signal bandwidth

The 3.3-4.2 GHz frequency of 5G NR Band n77 has a total bandwidth of 900 MHz, and it is challenging to cover such a wide band with a single PA.

Signal bandwidth is also one of the factors affecting the linearity of PA. The distortion component of the nonlinear characteristic of PA is not constant. For example, the amplitude and phase of the three or five order intermodulation will change with the amplitude and bandwidth of the input signal. This distortion component depends on the amplitude and bandwidth of the input signal, which is often called the memory effect of the power amplifier, which affects the linearity of the PA.

In the LTE system, the signal bandwidth of a single carrier is 20 MHz, and in consideration of CA, it can be extended to 2CC 40 MHz or even the potential 3CC 60 MHz. But in 5GNR, the signal bandwidth will be greatly improved, and the linear deterioration caused by the memory effect will be a key factor in the design. NSA operation of 5G NR also calls for concurrent UL in LTE and NR which further stresses the linearity requirement.

2) PAPR (peak-to-average power ratio)

PAPR is the ratio of peak power to average power. The peak power is the instantaneous peak power that occurs at a certain probability, usually 0.01% of this probability.

Because of the instantaneous high power of the signal, in order to guarantee the linear index at the instantaneous high power level, the power back off is usually used to guarantee the linearity, and it's related with the PAPR.

The PAPR of the input signal is related to waveform and modulation, from LTE to 5G NR, the UE uplink waveform from single carrier to multi carrier. Considering the higher order modulation, 5G NR PAPR compared to LTE will be significantly increased.

3) Cooling capacity

With the increase of temperature, PA performance including gain, Pout and PAE will degrade in the device product layout, and some devices close to PA will deteriorate as the working temperature increases.

HPUE (High Power User Equipment) application need to increase UE Pout from 23 dBm to 26 dBm, which means the heat generated from PA will also be double if we assume the PAE does not change. Also the smaller PA package size will increase the difficulty of thermal dissipation of PA. When designing PA, it is necessary to improve the heat dissipation ability of PA and reduce the working temperature of PA by reasonable and correct layout, adopting the appropriate PA structure, chip technology and packaging technology.



4) Cost

5G NR Band n77 has total bandwidth of 900 MHz, also the PAPR of 5G NR signal is significantly higher than the LTE signal, these challenges will lead to different architectures. Take PA as example, use a single PA single power supply structure, adopts multi PA multi power architecture; bring in ET technology, adding DPD in PA pathway.

The PA performance of different design methods will be different, and the cost of PA will vary greatly. In the process of introducing PA products into the 5G market, excellent product performance and reasonable product cost can make the product get better market recognition.

For the 5G NR RF front end, because of the increasing number of the RF path (more frequency bands, dual connection, MIMO, etc.), the number of RF front end is also increasing obviously. The size and cost of the RF front end must be lower enough, to ensure the terminal's size and cost. For the future RF front end design, the hardware integration and reuse would be the point of concern.

6.1.2 Sub-6GHz 5G Power Amplifier Design

6.1.2.1 3GPP Standard

1) Frequency band

There have been many proposals in 3GPP, with the most emphasis placed on 3300 to 3800 MHz as a primary target with an extension to 4200 MHz to support Japan region. Current 5G NR global major band requirements are shown in figure 6-4A.

Region	F Ne	W F	E F	xisting	Band	BW	Total BW		F	Band	BW	Total BW
Korea	3400	¹ нісн 3700	LOW	• нібн	Duna	300	300	1	^н ибн 26.50	29.50	3.00	3.00
EU	3400	3800	2570 3400	2620 3800	38 42+43	50 400	450		24.25 31.80	27.35 33.40	3.10 1.60	7.70
Japan	3600	4200	2496 3400	2690 3600	41 42	194 800	1494		40.50 27.50	43.50 29.50	3.00 2.00	2.00
U.S.	4400	4900	2496	2690	41	500 194	344		27.50 37.00	28.35 38.60	0.85 1.60	10.85
			2300	2400	48 40	100			64.00	40.00 71.00	7.00	
China	3300	3600	2555 3400	2655 3600	41B 42	100 300	790	L				
	4400 4800	4500 4990				190						

Figure 6-4A Current 5G NR global major band requirements

2) Power level

As is in the case for TDD LTE spectrum, we anticipate power class 2 and 3 to be deployed in early 5G systems.





Figure 6-5 Power classes of 5G NR device

3) Signal Bandwidth

In terms of other rough parameters for the sub 6 GHz RF front end, we see consensus building around a maximum channel bandwidth 100 MHz.

4) Waveform and modulation

The peak to average ratio of the 5G NR signal is 3 dB higher than an equivalent LTE waveform. From that we can expect impact to take the form of higher back off or higher average transmit powers. Another interesting observation is that for 5G CP-OFDM using different modulation, there is no significant difference in the CCDF function- meaning higher-order modulation has minimal impact on MPR and power back-off.



Figure 6-6 CCDF curves of CP-OFDF and SC-FDMA

In figure 6-7 we can find CCDF curves of some lower PAPR options, which can be used in cell edge areas as well as mmWave.

Some observations on lower PAPR aspects:

- DFT-s-OFDM QPSK waveform in UL , exhibits very similar PAPR as the existing LTE SC-FDMA used in UL
- shaped PI/2 BPSK is used for sub-6GHz , also assumed for mmWaves and provides up to 7.5 dB relief



Figure 6-7 CCDF curves of some alternate candidate waveforms

6.1.2.2 Design Challenges

1) RF path Co-banding

The frequency below 6GHz is still scarce resources. There may be LTE and 5G NR working on the same frequency band. Different operators will make different deployment between LTE and 5G NR.

As shown in table 6-1, it is possible for LTE to share the same RF path with 5G NR on UE. The co-path can not only save the hardware cost of the RF front-end devices, but also reduce the PCB area. Of course, this also requires LTE and 5G NR be fully aligned on the time slot, otherwise the coexisting interference problem will be caused.

LTE Band number	UL	DL	Duplex mode
B41	2496-2690 MHz	2496-2690 MHz	TDD
B42	3.4-3.6 GHz	3.4-3.6 GHz	TDD
B43	3.6-3.8 GHz	3.6-3.8 GHz	TDD
B48	3.55-3.7 GHz	3.55-3.7 GHz	TDD
NR Band number	UL	DL	Duplex mode
N41	2496-2690 MHz	2496-2690 MHz	TDD
n77	3.3-4.2 GHz	3.3-4.2 GHz	TDD
n78	3.3-3.8 GHz	3.3-3.8 GHz	TDD

Table 6-1 LTE and 5G NR frequency band around 3.5 GHz

There are have many challenges to achieve LTE and NR co-path, not only because the signal bandwidth of NR is much more than that of LTE, but also because NR needs to support PC2, and the peak to average ratio is higher, which leads to slight degradation of efficiency under LTE. At the same time, the coexistence requirement will also require the device to guarantee the intra-band RF performance defined by 3GPP.

For the RF front end, the Power amplifier must support both LTE and NR application in the same power amplifier. The ideal RF front end must be reconfigurable in different applications. There are many research results about the reconfigurable RF front end, which would be a

powerful support for the future RF front end application.

2) Interference in UE

Except the case that NR operation with only one UL band under SA mode, UE may suffer from in-device interference due to simultaneous UL transmissions in the NSA deployment and SUL under SA deployment.

There are three different types of in-device interference due to simultaneous UL transmission over different bands:

• Interference from Intermodulation (IMD)

This kind of interference comes from the intermodulation (IMD) product between lower-frequency and higher-frequency UL carriers, which may fall into the DL carrier. One example is that when a UE is transmitting simultaneously on B3 (LTE) and NR sub-6G band (3.3 - 4.2 GHz), interference of IM2/IM4/IM5 will fall into B1 LTE receiver.

• Interference from Harmonic

This kind of interference comes from the harmonic of lower- frequency UL signals to the higher- frequency DL signals when the harmonic of UL frequency falls into the DL frequency. One example is that when a UE is simultaneously transmitting on B3 (LTE) and receiving on NR sub-6G band B42 (3.4 - 3.6 GHz), interference from H2 of B3 will fall into NR receiver.

• Interference from Harmonic mixing

This kind of interference comes from higher frequency UL signals to the lower- frequency DL signals when the higher frequency is multiple of the lower frequency. One example is that when a UE is simultaneously transmitting on NR 3.3 - 4.2 GHz and receiving on LTE B26, interference from NR UL will fall into LTE B26 receiver and be demoded by receiver which causes sensitivity degradation.

3) Thermal Distribution

PA (Power amplifier) performance will degrade as temperature rises due to its device properties. Specifically, the higher the temperature, the lower its Gain, Output Power and Power Added Efficiency. In the end user equipment, some components such as Duplexers that are physically in adjacent with PA will experience performance degradation too. With the requirement of HPUE(High Power User Equipment) on devices, the output power at antenna will be increased from 23 dBm to 26 dBm, which means heat generated from PA will double assuming PA maintains same power added efficiency. In addition, a smaller footprint of PA makes heat dissipation even worse.

As a consequence, when designing a PA, one needs to take into account the architecture, process and assembly to improve the PA thermal distribution.

4) Cost

5G NR band 77 has large bandwidth (3.3 - 4.2 GHz). Its signal has higher PAR (Peak to Average Ratio) than that in LTE. Furthermore, different frequency bands inside 3.3 - 4.2 GHz have different output power requirements. These challenges call for different PA architectures, for example, single PA with single supply, or multiple PA paths with multiple supplies, EER (Envelop Elimination and Restoration) with traditional supplies or ET (Envelop Tracking) , DPT(Digital Pre-Distortion) in the PA signal path, etc.. All these factors will impact PA cost and performance, a good balance of which will help the acceptance by the marketplace of such 5G PAs.

6.1.2.3 Alternative Processes

There are only two foundries in China can provide the GaAs pHEMT process now, one is Hiwafer in Chengdu, the other is Sanan in Xiamen.

6-inch 2 um GaAs HBT process named as HBT02, can be used in high-frequency, high-linearity PA applied in cell phone, WiFi, Pad and other. This process is fit for sub-10GHz region: 4G LTE, 3G/2G, WiFi and base station. And provides two kinds of HBT, one is high β version, the other is low β version.

The BiHEMT process of HiWafer, which can be used to produce logic module and RF module simultaneous, is now under research. The development of BiHEMT process can increase the IC functional complexity and integration density.

The performances and measurement results of 6-inch 2um GaAs HBT process are given in table 6-2 and figure 6-8:

Deveryetye	HiWafer				
Parametre	HBT02				
Beta(V)	120(@1 kA/cm ²)	75(@1 kA/cm²)			
BVcbo(V)	24(@2 kA/cm ²)	24(@2 kA/cm ²)			
BVceo(V)	13(@2 kA/cm ²)	13(@2 kA/cm ²)			
ft/fmax(GHz)	40/60	40/60			
ResistorTaN(Ω/□)	50	50			
Capacitor(pF/mm ²)	600/930	600/930			
Au: M1/M2(μm)	1/2	1/2			

Table 6-2 Performances	of 6-inch 2 um	GaAs HBT process

The key parameters in table 6-2 are explained as follows:

- Beta(β): current gain, the 75-Gian transistor is commonly used in 3G, the 120-Gain transistor is commonly used in 4G and the later generations.
- BVcbo, BVceo: the breakdown voltage, the higher breakdown voltage means higher work voltage.
- ft: current cut-off frequency. The higher the ft, the better frequency characteristics.
- fmax: highest oscillation frequency, where the power gain of the transistor decreases to
 1.



Figure 6-8 Measurement results of 6-inch 2 um GaAs HBT process

GaAs device have the advantages of high electron mobility, low loss semi-insulating substrate, high linearity, high cut-off frequency, and high breakdown voltage, making them superior to CMOS in power performance. Therefore, GaAs device holds a dominant position in performance advantages over CMOS in the 4G PA market. For the future 5G PA market, the standard GaAs based modules will continue to maintain their advantages in power performance. In the whole market, compared with the highly integrated CMOS device and high power performance GaN device, GaAs device can continue to play its performance advantages by increasing its level of integration through processing and packaging.

Considering the fact that GaAs and silicon-based devices are still able to meet the cost and performance requirements. GaN device will not be used in 4G mobile phones for its still high working voltage. However, with the development of GaN technology, GaN device may be used in 5G mobile phone RF front-end module. Compared with high frequency devices such as GaAs and InP, the power density of GaN devices will be greater, which will help reducing the chip area of the PA. Compared with LDCMOS and SiC, GaN has better frequency characteristics; GaN device also has wider the instantaneous bandwidth, thus fewer amplifiers are needed to cover all bands and channels. GaN device has many other advantages, such as higher output impedance. High output impedance makes it easier for impedance matching and power combining of GaN device, and to cover a wider frequency range and improve the applicability of RF power amplifiers.

GaN applied in 5G phones, there are several problems need to be solved:

- GaN devices work in low voltage.
- The high thermal conductivity in cell phone
- High cost

6.1.2.4 Existing Sub-6GHz 5G Power Amplifier Products

- ≻ n41 PA
 - 1) Solution of n41 NR PA

Below chart is an example of a n41 dedicated Tx/Rx solution to be commercialized for 2019.



Figure 6-8A An example of a n41 dedicated Tx/Rx solution to be commercialized for 2019

The 5GNR capable FEM contains a full band n41 transmit PA, a receive LNA, a Tx/Rx switch and integrated filter. Dual directional coupler for power control and independent MIPI registers for Tx and Rx control.

The SKY58254 feature list is:

- 3 x 5 x 0.7 mm max
- Latest PA Engine supporting 100 MHz BW
- Full PC2 power and BW support with APT 5V operation
 - DPD is not necessary, but can be used as an adjunct to improve efficiency.
- Dual ET/APT modes are supported with internal APT CAP switch can be enabled for optimized APT Operation using a large external cap on board for APT modes. The external path is disabled for ET use case.
- Full B41 Filter HPUE capable
- FOR/REV CPL with CPL Switch and CPL_In
- Full BW LNA

This represents the mainstream performance, and we would expect variants to be developed as market matures.

2) Target APT Performance of n41



100MHz SCS30KHz								
MPR0=	28.5		4.2V					
						3GPP		
signal	Pout	ACPL	ACPH	EVM	Current	MPR		
QPSK DFT-S-OFDMA	27.5	-38	-38.9	1.5	845	1		
QPSK CP-OFDM	25.5	-37.8	-38.5	1.9	739	3		
64 QAM DFT-S-								
OFDMA	26	-39.8	-40.1	1.64	770	2.5		
64 QAM CP-OFDM	25	-39.4	-39.2	1.85	720	3.5		
256 QAM DFT-S-								
OFDMA	24	-42	-42	1.34	690	4.5		
256 QAM CP-OFDM	22	-42.7	-43.2	1.38	639	6.5		

Figure 6-8B Target APT Performance for n41



Figure 6-8C PAE Curves of n41 PA (5.5 V)

Note: Freq Centering needed to improve/optimize PAE from 2.4 - 2.6 GHz to 2.5 - 2.7 GHz PAE low by 2-3%, future MCM update will address the increase to PAE from this initial sample.









Figure 6-8E Gain/PSAT @ 2700 MHz with slight Load line Adjustment relative to 2500 MHz



Figure 6-8F Expected performance of filter in n41

3) Challenges from intra band EN DC, B41+N41:

GTI

The B41/n41 Dual Connectivity Use Case : DC_B41_n41

The existing B41 supporting LTE, and the 4G services will be appended with 5G services and migrate over time to eventually become an entirely 5G band.

Leveraging the existing wide LTE coverage, capacity, and customer base, along with the established LTE enhanced core packet (EPC) network, the build-out of the Non-Stand-Alone (NSA) architecture option 3 serves to enable continued use of the LTE back-haul and incrementally add NR radio heads on existing towers in a cost effective and rapid roll-out of 5G services.

This approach drives the intra-band EN-DC use case of DC_B41_n41, where 2 non-contiguous synchronous TDD channels; one LTE at one frequency and one 5G at a different frequency, operate concurrently within the same band. During uplink (UL) these 2 modulation clusters are transmitted concurrently and will encounter nonlinearities within the RF front-end, producing intermodulation products. The concentrated IMD products must be low enough in amplitude at the transmitting antenna that the UE is enabled to pass radiated emissions requirements at the problem offset frequencies where the IMD are generated. The 2 architectural options are:

- 1) single PA transmitting to a single antenna.
- 2) Dual PAs each transmitting separate signals (one for 4G, one for 5G) to 2 dedicated/separate antennas.

The single PA solution clearly has BW and linearity challenges in transmission of potentially widely spaced channels at vastly different frequencies within this 160MHz band, the penalty of higher peak-to-average for the 2CC channel vs. each separate signal alone which forces MPR and additional headroom and lower efficiency in order to transmit the combined signals linearly. Additionally, the forward IMD which is a huge challenge to manage the concentrated



emissions at the antenna.

The Dual PA/2Antenna solution addresses many of these issues with more manageable instantaneous modulation BW of each channel separately, the peak-to-average and power capability is much more optimum for the separate signals and lower peak-to-average, and the IMD products are no longer a result of running the 2 signals through the nonlinear gain of a single PA with a strong forward IMD nonlinear mechanism, but instead dominated by the finite antenna isolation and an attenuated version of the other Tx path signal then back-injected at the output of the active PA and a Reverse IMD mechanism.

The reverse IMD mechanisms is slightly better/lower relative to the worse Forward IMD mechanism, and the fact that the back-injected aggressor from the other antenna is lower by the amount of the antenna-to-antenna isolation makes a large difference overall in the Reverse IMD generation. As shown in figure 6-8G, the various RF leakage paths at the inputs of the PAs and at the outputs due to finite antenna isolation are illustrated for the 2PA/2Antenna solution.





The other critical aspect of the IMD that is then created and present at the output of the PA may get attenuated on its way to the antenna where we must meet the emissions requirements.

As shown in figure 6-8H, if the LTE and NR channels are offset from one another by a large frequency difference, then the resulting IMD products will also be further away, and in some cases far enough away that the B41 filter can provide some strong selectivity and attenuation to easily meet the antenna emissions. The more difficult cases tend to be those produced by closely spaced LTE and NR channels that then fall in band and do not benefit from such filter selectivity.

2680



Figure 6-8H Channel location and resulting IMD in-band or out-of-band cases, demonstrating the opportunities for OOB IMD to easily pass antenna emissions requirements

2506

The magnitude of the IMD products will depend as indicated on the architecture, but also the behavior of the power amplifier itself. This is particularly true when considering saturated PAs in Envelope Tracking (ET) solutions, where the intrinsic PA nonlinearity is worse than the linear fixed Vcc supply voltage solution of an APT PA. Bandwidth capabilities are also more relaxed for the APT linear PA as an additional advantage for that PA solution, but with some degradation in overall efficiency and current consumption.

➢ n78/n79 PA

1) Solution for n78/n79

Currently, the RF front-end module that supports 3.3 - 4.2 GHz and 4.4 - 5 GHz for 5G NR 3GPP standards is under develop, and a conceptual image of the fully technology demonstrator for sub 6 GHz TDD systems in 3.5/4.5 GHz could look like this. Actual Implementation is likely to vary, but the main concepts remain intact.





Figure 6-9 Block diagram of RFFE module support 3.3 - 4.2 GHzand 4.4 – 5 GHz

The PA in the sub-6 GHz module will be assumed to be LTE and 5G NR compatible. The PA will have to be designed to support power class 2 HPUE in at least some sections of the band. In general, Support for:

- LTE and 5GNR PC 3 and PC 2
- CP-OFDM and DFT-s-OFDM waveforms
- Full and Partial allocations (at channel edge and in-channel)
- 20MHz and 100MHz bandwidths
- QPSK, 16QAM and 64QAM
- Normal, clipped or low PAPR waveforms

As shown in figure 6-10, we use CP-OFDM QPSK Full RB waveform and 3.8 V power supply, PA Engine can achieve 26.9 dBm@100MHz for -36 dBc ACLR, almost same power capability is maintained for 200 MHz and 400 MHz channel bandwidths.

Scale	/Di	v 10.0 dB		_		Ref Value 20.	00 dBm				
Log 10.0 0.00 -10.0		· -5	2.8 dBc	-37	6 dBc	26.0	dBm	-36.3	dBc	-53.3 c	iBc
-20.0 -30.0 -40.0						/					
-50.0											
Cente #Res	er 3 BV	.5 GHz V 220 kHz				Video BW 22.0	000 kHz*			Sj weep Time 267	pan 519.6 MH: ms (1001 pts







Figure 6-10 ACLR test results based on MP PA engine

In figure 6-11, shows the corresponding changes of linearity and efficiency





PS: all the figures above are provided by Skyworks.

2) Measured Data of Sub-6GHz 5G NR PA

Now according to 5G NR Standalone 3GPP specification, supporting Band n77 3.3 - 4.2 GHz 900 MHz bandwidth RF front end module is already developed. The block diagram is in figure 6-12


Figure 6-12 5G NR RF Front End Module Block Diagram

This RF Front End Module integrates power amplifier, Tx/Rx pass band filter, LNA, Switch and coupler.

Supporting linear output power 24.5 dBm (Power Class 3) at Ant port.

- a) Supporting high PAR of ~9 dB 5G CP-OFDM modulation
- b) Supporting max CA bandwidth of 400 MHz, 4CC
- c) Supporting QPSK/16QAM/64QAM modulation signal
- d) Supporting 2 dB max power back off to 22.5 dBm (single carrier 100 MHz bandwidth and 64QAM modulation signal)
- e) Supporting 3 dB max power back off to 21.5 dBm (4CC 400 MHz bandwidth and 64QAM modulation signal)
- f) Supporting APT technology

Detailed RF front end module measurement condition and data are as below:

- a) Test Condition
 - Linear 22.5 dBm output power at Ant port
 - CP-OFDM 5GNR input waveform
 - Single carrier 100 MHz bandwidth
 - 64QAM modulation
 - 4.5 V constant supply voltage
- b) Test Data

The module Tx Gain from 3.3 - 4.2 GHz 900 MHz bandwidth is from 24 – 26 dB





Figure 6-13 5G NR RF Module Gain data





Figure 6-14 5G NR RF Module power consumption based on different duty cycles

F Module ACLR within 3.3 - 4.2 GHz is less than -36 dBc.



Figure 6-15 5G NR RF Module ACLR

RF Module EVM within 3.3 - 4.2 GHz is less than 3.5%.



Figure 6-16 5G NR RF Module EVM Data

Note: Above RF Module information and data are provided by Qorvo.

Currently, for the 5G-NR Standalone 3GPP specification, an RF front-end module supporting Band n41 2.5 -2.7 GHz 200 MHz bandwidth has been developed. The block diagram is shown in Figure 6-16A.









Figure 6-16B 100MHz_SCS 30KHz_Pi/2-BPSK_134RB_67SRB_DFT-s_OFDM – PC2





Figure 6-16C 100 MHz_SCS 30 KHz_Pi/2-BPSK_134RB_67SRB_DFT-s_OFDM – PC2

6.1.2.4 Picture and product information in chapter 2) Source: Qorvo

3) System Diagram of Sub-6GHz 5G NR PA

Vanchip is developing a 5G RFFEM (RF Front End Module) supporting 3.3 - 4.2 GHz. figure 6-17 below is the system diagram.



Figure 6-17 5G NR RF Front End Module Diagram

In Solution A, a 3.3 - 4.2 GHz PA, a coupler, a LNA (low noise amplifier) and SPDT switch are integrated in a single module. Customers can place the filter on PCB to meet their requirements on performance and cost.

In Solution B, filter is placed into the module to optimize the module performance and to achieve the maximum integration for customers.

Both solutions support requirements as below:

- a) PC2, PC3 in 5G NR and LTE
- b) QPSK/16QAM/64QAM Modulation
- c) CP-OFDM and DFT-s-OFDM Waveform
- d) Maximum 400 MHz 4 Carrier Aggregation
- e) APT and ET

Reconfigurable n77/79 L-PAMiF

1) Reconfigurable solution for n77/79 L-PAMiF

For n78/79 NR bands, frequency at 3.3 - 4.2 GHz and 4.4 - 5.0 GHz respectively, lots of challengers have been introduced to PA design. Such as more insertion loss due to high frequency, more output power requirement for HPUE scenario, more cost due to 2T4R requirement.

Below chart is an block diagram of n77/79 PA module, which using reconfigurable technology with SOI + GaAs HBT hybrid process.





Figure 6-17A Block diagram of RFFE module for n77/79 using reconfigurable technology

PS: Figure 6-17A is provided by SmarterMicro.

The PA takes advantage of wide band optimization by reconfigurable technology, designed the only one PA path supporting both n77 and n79. The RX LNA also keeps only one path for n77 and n79, because of the flexible SOI CMOS process.

The L-PAMiF integrated reconfigurable PA and LNA, LTCC/IPD filters and SRS switch. The feature list as below:

- Supports CP-OFDM and DFT-s-OFDM waveforms
- Uplink supports QPSK, 16QAM, 64QAM and 256QAM modulation
- Supports LTE and NR PC3 and PC2
- Supports up to 100 MHz bandwidth
- Supports full SRS hopping with minimal external switches
- Supports up to 2x2 UL-MIMO and 8x8 DL-MIMO
- 2) Design challenges for n77/79 L-PAMiF
 - a) Ultra wide band optimization for n77/79 reconfigurable PA design

Most of the 4G and 5G PA were developed by GaAs HBT process, due to the inflexibility and transistor performance of GaAs HBT process, the PA can't be designed in very wide band support. Hence, to support n77 and n79 NR bands, most companies developed two PAs to support n77 and n79 respectively. Obviously, the cost of such a scheme is inevitably high.

Using reconfigurable technology can develop only PA path for both n77 and n79 bands. The total frequency bandwidth will be 1.7GHz, from 3.3 GHz to 5.0 GHz, is really wide band for PA design. How to optimize PA support 5G high performance requirements at all the frequency point becomes a very tough work.



Fortunately, the SOI CMOS process provides a very flexible platform for circuit design. For example, developing a tunable matching network for ultra-wide band PA impedance matching. Many technologies will be introduced into the commercial PA design, such as adaptive AMAM/AMPM contral, frequency adaptive matching technique, pre-distortion circuits.

b) Memory effect at wide band PA design

As the signal bandwidth increasing to 100 MHz at NR era, the PA memory effect plays an important role at PA linearity performance, and always makes the performance worse. Predictably, the signal bandwidth of 5G will larger than 100MHz, hence the memory effect will be a very tough issue to overcome.

Using SOI + GaAs hybrid technology maybe a good choice to overcome the memory effect, the GaAs HBT stage provide the high power capability, and the SOI stage can develop an adaptive circuit to compensate the memory effect.

c) The interference in EN-DC scenario

Currently, many operators start develop NSA NR network. Hence, the interference in EN-DC scenario can't be ignored.

At EN-DC scenario, for example LTE B3 + NR n78, LTE and NR are simultaneously working at the same time. Predictably, the 2nd order harmonic of B3 may fall into n78 receiver, the n78 PA spurious emission at B3 receiver band may also interfere B3 receiver.

3) System diagram for n77/79 L-PAMiF solution

The n77/79 L-PAMiF module supports all the MIMO requirements, the most popular MIMO system block diagrams are shown below:



Figure 6-17B NR RFFE 2T4R system block diagram



Figure 6-17C NR RFFE 1T4R system block diagram

The figure 6-17B shows the 2T4R MIMO RFFE system, and the figure 6-17C shows the 1T4R MIMO RFFE system.

6.2 Sub-6GHz 5G Filter

6.2.1 Existing Mobile Device Commercial Filter

The rapid growth in mobile wireless data and 4G LTE networks has created an ever-increasing requirement for new spectrum bands to accommodate wireless traffic. Whereas 3G networks used only about five bands, there are already over 20 4G LTE bands and this number could rise to more than 40 in the near future.

Though it's not practical to support all worldwide bands in a single smartphone, a feature-rich model for international use may need to filter transmit and receive paths for 2G, 3G, and 4G in up to 15 bands, as well as Wi-Fi, Bluetooth, and global navigation satellite system (GNSS). Such a phone may require as many as 30 to 40 filters. The situation is likely to become even more complex with next-generation high-end smartphones requiring even more filters.

6.2.1.1 Common Types of Filter

A filter removes unwanted frequency components from a signal while preserving desired frequency components. There are four basic types of filters that accept or reject signals in different ways (see figure 6-18). The different types are defined as

- Low pass: Allows all frequencies below a certain frequency to pass while rejecting all others (opposite of high pass)
- High pass: Allows all frequencies above a certain frequency to pass while rejecting all others (opposite of low pass)
- Band pass: Allows all frequencies between two frequencies to pass while rejecting all others (opposite of band stop)
- Band stop (or band reject): Rejects all frequencies between two frequencies while passing all others (opposite of band pass)

Band stop and band reject filters are also known as notch filters.



Figure 6-18 Basic Filter Types

Filter construction varies by application, with size, cost, and performance the major variables. Here are some example filter constructions:

- Discrete inductor-capacitor (LC) filters are low-cost structures of moderate performance and size. The LC elements are sometimes implemented as printed structures on substrates called an integrated passive device (IPD).
- Multilayer ceramic filters are low to moderate cost and have similar performance to LC filters. Their footprint is generally reasonable, but their thickness is becoming an issue as mobile applications emphasize thinner and thinner designs.
- Monoblock ceramic filters are much higher performance than multilayer ceramics and also more expensive. They're also physically larger and usually aren't suitable for mobile applications.
- Acoustic filters have the capability to meet both low and high frequencies up to 6 GHz, are small in size, and offer the best performance and cost for complex filter requirements. Acoustic filters are the most common filter construction for mobile devices.
- Cavity filters are used in infrastructure applications only. They can achieve good performance at reasonable cost but are large.

6.2.1.2 Key Parameters and Influence Factors

Filters can be designed to meet a variety of requirements. Although they use the same basic circuit configurations, circuit values differ when the circuit is designed to meet different criteria. In-band ripple, fastest transition to the ultimate roll-off, and highest out-of-band rejection are some of the criteria that result in different circuit values. Filters allow only

particular frequencies or bands of frequencies to pass through and are, thus, an essential tool for RF design engineers. Typical filter response curve is shown in figure 6-19.



Figure 6-19 Typical Filter Response Curve

In case your knowledge of electronics is a bit rusty, here's a brief tutorial on some of the more important terms and concepts to help refresh your memory.

- 1) Attenuation: An amplitude loss, usually measured in decibels (dB), incurred by a signal after passing through an RF filter.
- 2) Cutoff: Normally taken to be the point at which the response of the filter has fallen by 3 dB.
- 3) Group delay: The derivative of a filter's phase with respect to frequency. Group delay, measured intime (in seconds), can be thought of as the propagation time delay of the envelope of an amplitude modulated signal as it passes through an RF filter.
- 4) Insertion loss: Loss of signal power resulting from the insertion of a component.
- 5) Isolation: Separation of one signal from another to prevent unintentional interaction between them (for example, transmit and receive interaction).
- 6) Q factor: The "quality" factor is a measure of the selectivity of a resonant circuit described as the ratio of stored versus lost energy per oscillation cycle.
- 7) Passband: The region through which the signal passes relatively unattenuated.
- 8) Ripple: The variation of insertion loss in the passband.
- 9) Selectivity: A measurement of the capability of the filter to pass or reject specific frequencies relative to the center frequency of the filter. Selectivity is usually stated as the loss through a filter that occurs at some specified difference from the center frequency of the filter.



10) Stopband: A band where the filter has reached its required out-ofband rejection, defined as a required number of decibels.

The figure shows some clear trends:

- 1) Loss increases as the Q factor drops and increases more rapidly for lower values of resonator Q.
- 2) The edges of the passband become more rounded and the passband narrower as the Q decreases. Note how each successively lower Q plot fits inside the previous.
- 3) The loss at the passband edges increases more than loss in the middle of the band. This poses a serious problem for modulations that go right to the edge of the passband.



Figure 6-20 Acoustic Filter Attentuation based on different Q

Narrow modulations such as GSM (200 kHz) and CDMA (1.25 MHz) will suffer the most sensitivity loss at the band edge due to this effect, while WCDMA (3.84 MHz) will suffer less. LTE results depend on the system bandwidth, with narrower bandwidths more affected.

6.2.1.3 Acoustic filter

Acoustic filter technologies continue to evolve to meet the challenges of the global transition to 4G networks. In this chapter, you find out about surface acoustic wave (SAW) and bulk acoustic wave (BAW) filter technologies, which are used to solve many of today's toughest mobile device filtering problems.

1) SAW: Mature But Still Growing

SAW filters are widely used in 2G and 3G receiver front ends, duplexers, and receive filters. SAW filters combine low insertion loss with good rejection, can achieve broad bandwidths, and are a tiny fraction of the size of traditional cavity and ceramic filters.

Because SAW filters are fabricated on wafers, they can be created in large volumes at low cost.

SAW technology also allows filters and duplexers for different bands to be integrated on a single chip with little or no additional fabrication steps.

The piezoelectric effect that exists in crystals with a certain symmetry is the 'motor' as well as the 'generator' in acoustic filters. When you apply a voltage to such a crystal, it will deform mechanically, converting electrical energy into mechanical energy. The opposite occurs when such a crystal is mechanically compressed or expanded. Charges form on opposite faces of the crystalline structure, causing a current to flow in the devices and/or voltage between the devices. This conversion between electrical and mechanical domains happens with extremely low energy loss, achieving exceptional efficiency inboth directions.

In solid materials, alternating mechanical deformation createsacoustic waves that travel at velocities of 3,000 to 12,000 meters per second. In acoustic filters, the waves are confined to create standing waves with extremely high-quality (high-Q) factors of several thousand. These high-Q resonances are the basis of the frequency selectivity and low loss that acoustic filters achieve.

In a basic SAW filter (see figure 6-21), an electrical input signal is converted to an acoustic wave by interleaved metal interdigital transducers (IDTs) created on a piezoelectric substrate, such as quartz, lithium tantalite (LiTaO3), or lithium niobate (LiNbO3). Its slow velocity makes it possible to fit many wavelengths across the IDTs in a very small device.



Figure 6-21 SAW Filter Architecture

A key advantage of SAW is its capability to optimally meet standard filter applications up to 1.9 GHz, including several standard bands such as GSM, CDMA, 3G, and some 4G bands.

Additionally, techniques such as wafer level packaging (discussed in Chapter 6) are being used to shrink SAW filters, allowing the integration of filters and duplexers for multiple bands onto a single chip. This is becoming increasingly important as smartphones incorporate more functions.

SAW filters, however, have limitations. Above about 1 GHz, their selectivity declines, at about 2.5 GHz.

The use of SAW is limited to applications with modest performance requirements SAW is also very temperature sensitive, this issue is better handled by temperature compensated SAW technology (TC-SAW). The stiffness of the substrate material tends to decrease at higher temperatures and acoustic velocity diminishes. A SAW filter's response may shift downward by as much as 4 MHz as temperature increases. This limitation has become more significant as guard bands become narrower and consumer devices are specified to operate across a wide temperature range (typically, -20° C to 85°C).

2) BAW: High Performance

BAW filters generally deliver superior performance (higher Q) with lower insertion loss at higher frequency levels. With BAW technology, it is possible to create narrowband filters with exceptionally steep filter skirts and excellent rejection. This makes BAW the technology of choice for many challenging interference problems. BAW delivers these benefits at frequencies above 1.5 GHz, making it a complementary technology to SAW (which is most effective at lower frequencies). BAW can address frequencies up to 6 GHz and is used for many of the new LTE bands above 1.9 GHz. BAW is also highly effective for LTE/Wi-Fi coexistence filters.

BAW filter size also decreases with higher frequencies, which makes these filters ideal for the most demanding 3G and 4G applications. In addition, BAW design is far less sensitive to temperature variation even at broad bandwidths.

Unlike SAW filters, the acoustic wave in a BAW filter propagates vertically (see figure 6-22). In a BAW resonator using a quartz crystal as the substrate, metal patches on the top and bottom sides of the quartz excite the acoustic waves, which bounce from the top to the bottom surface to form a standing acoustic wave. The frequency at which resonance occurs is determined by the thickness of the slab and the mass of the electrodes. At the high frequencies in which BAW filters are effective, the piezo layer must be only micrometers thick, requiring the resonator structure to be made using thin-film deposition and micro-machining on a carrier substrate.



Figure 6-22 BAW Filter Architecture

To keep the waves from escaping into the substrate, an acoustic Bragg reflector is created by stacking thin layers of alternating stiffness and density. The result of this approach is called a

solidly mounted resonator BAW (BAW-SMR). A Bragg reflector is a structure formed from multiple layers of alternating materials with varying refractive index.

An alternative approach, called a film bulk acoustic resonator (FBAR), etches a cavity underneath the active area, creating suspended membranes. Figure 6-23 compares BAW-SMR and FBAR filter designs.



Figure 6-23 FBAR Vs BAW-SMR Architecture

Both types of BAW filters can achieve very low loss because the density of their acoustic energy is very high and the structures trap acoustic waves very well. Their achievable Q is higher than any other type of filter of reasonable size employed at microwave frequencies: 2,500 at 2 GHz. This results in superb rejection and insertion loss performance, even at the critical pass band edges.

The fundamental difference between FBAR and BAW-SMR is in how acoustic energy is trapped. For FBAR, the air/crystal interface on both faces of the resonator ensures that the main mode of interest is appropriately trapped. In BAW-SMR, Bragg reflectors underneath the resonator effectively trap this mode. Another major difference between FBAR and BAW-SMR is the thermal path for heat generated in the device. In BAW-SMR, the heat has a conduction path into the substrate from which it can be spread. In FBAR, because there is an air gap on each side of the resonator, the thermal conduction path is weaker.

Because BAW filters offer low insertion loss, they help compensate for the higher losses associated with the need to support many bands in a single smartphone. Besides improving signal reception, lower loss also contributes to longer battery life. BAW excels in applications where the uplink and downlink separation is minimal and when attenuation is required in tightly packed adjacent bands.

Figure 6-24 Void

6.2.1A2.4 - 2.7 GHz 5G Filter Design

6.2.1A.1 Design Challenges

These products had been originally developed for TD-LTE. Assuming these products can also be used for n41 while new conditions and/or requirements are under investigation.



6.2.1A.2 Alternative Processes

According to present information, we believe that SAW or FBAR process products can meet the requirements of 5G n41 characteristics.

6.2.1A.3 Existing 2.4 - 2.7 GHz 5G Filter Products

The following is the TAIYO YUDEN filter product for n41 band based on SAW or FBAR technology. The main performance has been shown at below tables and figures. table 6-2A, figure 6-2B, figure 6-24A and Figure 24B:

Pass band Frequency	2535-2655 MHz		
Insertion Loss(Type)	1.7 dB		
	2400 - 2483 MHz	38 dB	
Attenuation(Type)	2750 – 4900 MHz	33 dB	
	4900 – 6000 MHz	45 dB	
	6000 – 8000 MHz	32 dB	
Power Capability*	+31 dBm at 2535 - 2655 MHz, 5000 Hr		
	+32 dBm at 2535 - 2635 MHz, 5000 Hr		
Size	1.1 mm x 0.9 mm x 0.44 mm MAX		

Table 6-2A SAW Filter for 5G Band n41 (120MHz) HPUE

* The power handling test condition for 5G NR (CBW: 100 MHz) is under investigation.



Figure 6-24A Frequency Performance of SAW Filter for 5G Band n41 (120 MHz) HPUE

Comments: Above actual test data is provided by TAIYO YUDEN.

Table 6-2B FBAR Filter for 5G Band n41 (194 MHz) HPUE



Pass band Frequency	2496 – 2690 MHz			
Insertion Loss(Type)	2.4 dB	2.4 dB		
	2401 - 2483 MHz	35 dB		
Attenuation(Type)	2775 – 4992 MHz	14 dB		
	4992 – 5380 MHz	34 dB		
	7488 – 8070 MHz	23 dB		
Power Capability*	+32 dBm at pass band frequency, 5000 Hr			
Size	1.8 mm x 1.4 mm x 0.57 mm MAX			

* The power handling test condition for 5G NR (CBW: 100 MHz) is under investigation.



Figure 6-24B Frequency Performance of FBAR Filter for 5G Band n41 (194 MHz) HPUE

Comments: Above simulation data is provided by TAIYO YUDEN.

6.2.2 3.3GHz-4.2GHz 5G Filter Design

6.2.2.1 Design Challenges

RFFE architecture for 5G which is being introduced worldwide would further require higher frequency and wider frequency bandwidth as it was standardized under 3GPP Release 15. Filtering devices would be required to cover rather much higher relative bandwidth ratio as opposed to current 4G requirement as well as the compatibilities to HPUE requirement which has already been standardized within Release 15 while filtering devices are expected to provide rather lower insertion loss as well as decent attenuation level. Furthermore, when

initial 5G implementation is done by NSA (Non-Standalone) mode, this may possibly generate IMD issue which would require filtering devices to provide lower passive inter-modulation characteristics. Therefore, upcoming new filtering RF devices must consider satisfying these potential issues as well.

6.2.2.2 Alternative Processes

Combine with 6.2.1.3 introduction of SAW filter, as the following chart 6-25, at the present the technology of filters have been divided to 3 series: ONE is SAW technology, it has always been utilized for main bands of cellular phone standard and this should continue to be the case as 5G will be using existing LTE bands after refarming by 3GPP. But it is difficult to meet the requirement of 5G high frequency and wider frequency bandwidth; TWO is FBAR/BAW technology, it has mainly been utilized for satisfying rather stringent attenuation and somewhat higher frequency requirement especially for the solution of coexistence with adjacent systems. This technology is capable of covering up to approximately 3800 MHz ranges while the company has been working to push the envelope toward even much higher frequency ranges especially to satisfy upcoming 5G requirement. THREE is LTCC (Low Temperature Co-fired Ceramic) technology. It is capable of meeting wider frequency bandwidth and higher frequency requirement. Similar to LTCC, LC structures on IPD technology, while a bit lower Q, are essential for integration in modules covering PA, switch, LNA and filters for frequencies above 3.3GHz, thanks to its miniaturization capabilities.



Figure 6-25 Common Filter Technologies

6.2.2.3 Existing 3.3 - 4.2 GHz 5G Filter Products

1) Technological advantages of multilayer ceramic filters (LTCC)

With the utilization of multilayer ceramic technologies, it can provide extremely low insertion loss for Sub-6GHz while covering entire required bandwidth. The relative bandwidth that can be covered with multilayer ceramic filters is approximately from 5 to 50%. It also contributes to the downsizing and lower profile requirements with significantly stable performance and relatively low cost. This technology also provides rather high power handling capabilities in comparison with SAW technologies and this should be another advantage as HPUE should be required by 5G Sub-6GHz standard. On the other hand, multilayer ceramic filters provide rather relaxed skirt characteristics as opposed to SAW filter technology. This concept should directly be applied to 5G Sub-6GHz requirement including Band n77, n78 and n79.

At the present, there is 5G LTCC filter already can support the HPUE device of Band n77 and Band n78, the main performance has been showed at below sheets and table 6-3, figure 6-26 table 6-4, figure 6-27.

Pass band Frequency	3.3 – 4.2 GHz			
Insertion Loss(Type)	1.13 dB			
Attenuation(Type)	600 – 2700 MHz	44.4 dB		
	4900 – 5900 MHz 32.4 dB			
	6600 – 8400 MHz	44.1 dB		
	9900 – 12600 MHz 32.4 dB			
Power Capability	+33 dBm at pass band frequency, 10000 Hr			
Size	2.0 mm x 1.25 mm x 0.65 mm MAX, LGA Package			

Table 6-3 Multilayer Ceramic Band Pass Filter for 5G NR Sub	o-6GHz Band n77 HPUE
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Figure 6-26 Frequency performance of LTCC BPF for 5G NR Sub-6GHz Band n77 HPUE

Note: Above actual test data is provided by TAIYO YUDEN.

Table 6-4 Multilayer Ceramic Band Pass Filter for 5G NR Sub-6GHz Band n78 HPUE

Pass band Frequency	3.3 – 3.8 GHz



Insertion Loss(Type)	1.24 dB			
	600 – 2700 MHz	42.3 dB		
Attenuation(Type)	4900 – 5900 MHz	39.1 dB		
	6600 – 8400 MHz	44.7 dB		
	9900 – 12600 MHz 36.5 dB			
Power Capability	+33 dBm at pass band frequency, 10000 Hr			
Size	2.0 mm x 1.25 mm x 0.65 mm MAX, LGA Package			



Figure 6-27 Frequency Performance of LTCC BPF for 5G NR Sub-6GHz Band n77 HPUE Note: Above simulation data is provided by TAIYO YUDEN.

2) Integrated n77 filte

Below is integrated filter supporting 5G Band n77



Figure 6-28 n77/n78 5G RF FEM Block Diagram

Tx chain gain data is as below



Figure 6-29 RF FEM Tx Gain Data

6.2.3 4.4GHz-5GHz 5G Filter Design

6.2.3.1 Design Challenges

3GPP RAN4 members have come to the agreement to choose the band from 4.4 GHz to 4.99 GHz earlier, on the other hand, as China MIIT (Ministry of Industry and Information Technology) published additional frequency ranges for 5G trial, including 4.8 - 5 GHz. This was also proposed within 3GPP RAN4 and it has been approved that the upper edge of Band n79 was extended from 4.99 GHz to 5 GHz to support the spectrum demand in China. Within 3GPP, Band "n79" was newly assigned for "4.4 - 5 GHz". Same as the filter for sub-6GHz 5G NR, the filters for 4.4 - 5 GHz need to support wider frequency bandwidth and higher frequency. Other technology or integrated technologies shall be utilized depending upon the attenuation requirement of adjacent systems such as WiFi 5 GHz and/or LAA/eLAA which starts at 5.15 GHz.

6.2.3.2 Alternative Processes

Same as 6.2.2.2, LTCC technology is capable of meeting wider frequency bandwidth and higher frequency requirement.

6.2.3.3 Existing 4.4 – 5 GHz 5G Filter Products

1. Introduction of LTCC filter and related performance

Technology background of this Band n79 LTCC filter is same as previously explained in the article of Band n77 filter. LTCC based filter design is rather flexible and the design can be applied to other type devices including low pass filter, band pass filter, diplexer for Sub-6GHz in the light of upcoming 5G requirement. At present, Taiyo Yuden has been working on series of different band pass filters for 5G Band n79 and the following is the example from the variations and the size is 2.0 mm x 1.25 mm x 0.65 mm Max with LGA (Land Grid Array) package and performance is as shown as below table 6-5, figure 6-30.

Table 6-5 Multilayer Ceramic Band Pass Filter for Sub-6GHz 5G NR Band n79 HPUE



Pass band Frequency	4.4 – 5 GHz		
Insertion Loss(Type)	0.55 dB		
Attenuation(Type)	2400 – 2500 MHz	50.6 dB	
	2500 – 2690 MHz 39.9 dB		
	8800 - 10000 MHz	22.1 dB	
	13200 – 15000 MHz 31.7 dB		
Power Capability	+33 dBm at pass band frequency, 10000 Hr		
Size	2.0 mm x 1.25 mm x 0.65 mm MAX, LGA Package		



Figure 6-30 Frequency Performance of LTCC BPF for Sub-6GHz 5G NR Band n79 HPUE

Note: Above simulation data is provided by TAIYO YUDEN.

2. Integrated n79 filter

5G bands have higher frequency and wider band width, which requires filters provide more steep conversion bandwidth, these new requirements and characteristics bring great challenges to the existing acoustics based filters. The integrated passive filter which can be used in n79 device design provides a balance in performance, size and cost. Integrated n79 filter is still under development.

6.2.3.4 Coexistence between n79 and 5GHz WiFi

The ever-increasing demand for higher data rates and lower buffering times has driven the continuous evolution of cellular communication and transmission. 5G promises to take communication to levels we have never seen before, and there has been more pressure to deploy 5G handsets than any previous cellular standard. With this urgency to release 5G smartphones, potential Wi-Fi coexistence issues had been largely ignored even though Wi-Fi and 5G/Cellular are complementary technologies and effective coexistence of the two technologies would greatly enhance user experience. Wi-Fi data usage can reach as high as 92% based on various analytics reports^{[31][32]}. The 5 GHz Wi-Fi channel (802.11a/n/ac/ax) is being widely implemented in user equipment (UEs) across the world and it offers additional

spectrum beyond the traditional 2.4 GHz spectrum. Combined with the high speeds available in 5G, the efficient utilization of both Wi-Fi and 5G spectrum has the potential to offer substantially increased data rates with negligible latency. Therefore, it is important that Wi-Fi remains an integral part of smartphone use and complements 5G in order to provide the optimal user experience.

Due to close proximity of cellular channels and Wi-Fi channels in both 2.5 GHz and 5 GHz spectrum, efficient utilization of both Wi-Fi and NR spectrums can cause interference between Wi-Fi and cellular operation. Wi-Fi 2.4 GHz channel is adjacent to the n41, n40, and n7 spectrum and N79 is adjacent to the Wi-Fi 5 GHz channel (Figure 6-30A).







Fig 6-30B. interferences in the N79-Wi-Fi 5GHz co-existence cases.

To date, there has not been any requirement from carriers or OEMs for n79 coexistence with 5 GHz WI-FI channels and the current RF front-end (RFFE) implementation does not take this account. This can result in a significant desense in 5GHz Wi-Fi channels if no additional 58



measures are taken.

As an example, the SKY58255 module shown below (Fig. 6-30C) is an Ultra High Band transmit/receive module supporting n77-n79. This module is currently being designed into multiple phones in China and overseas markets, however, since coexistence with Wi-Fi was not considered as design target, there will be significant Wi-Fi desense (Table 6-5A).



Fig 6-30C. SKY58255 n77, n78 and n79 Tx/Rx module

Table 6-5A: Current n79 LPAMID/DRX rejections without use of high rejection filtering with native filtering inside the module

Rejection/Frequesncy (MHz)	5150	5350	5550	5750	5850
Wi-Fi 5 rejection from LPAMiF n79 Tx	-2.1	-3.2	-5.3	-8.2	-9.9
Expected Desense in Wi-Fi 5	36.4	30.5	18.8	13.7	11.6

The use of external high rejection filters and AntennaPlexers as shown in Fig 6-30D can help remedy this issue. With rejections up to 25-35 dB such as the ones offered by Skyworks AntennaPlexers, the desense is greatly improved and enables the end user device to achieve the co-existence needed for proper utilization for both spectrums. Table 6-5B below shows the enhancement.



Figure 6-30D Antennaplexers for Improved Coexistance

Rejection	5150	5350	5550	5750	5850
WIFI5 rejection from LPAMiF n79 Tx	-2.1	-3.2	-5.3	-8.2	-9.9
Rejection with High Rejection AntennaPlexer	-22	-22.2	-23.5	-30.8	-25.8
Combined Rejection	-24.1	-25.4	-28.8	-39	-35.7
Expected Desense in WIFI5 with Combined Rejection	14.6	8.9	1.3	0.1	0.2

Table 6-5B: Improved Desense Performance with AntennaPlexers

While there are some software based techniques available to help improve coexistance performance, the Use of Hardware Filtering for coexistance can offer multiple advantages including highest throughput that translates directly into faster data rates. The hardware filtering is platform agnostic which offers OEMs a flexibility to use transceiver platform of their choice. It also removes and restriction of Wi-Fi and user is able to benefit from Hotspot or External-AP modes. Most importantly, hardware filtering is future proof so any additional band combinations would not affect the filtering as 5G continues to evolve and new bands are allocated.

An example of hardware filtering is N77-79 AntennaPlexer, which offers high rejection of > 25 dBm with low insertion loss and enables co-existence between Wi-Fi and N79 frequencies (Fig 6-30E).



Fig 6-30E: Plot demonstrating High Rejection Filtering with N77/79 AntennaPlexer (Not to Scale)

A similar concept can be extended to the MHB-Wi-Fi 2.4 filtering to enable N41-Wi-Fi 2.4 and N7-Wi-Fi 2.4 co-existence. External implementation of the filter also affords flexibility in some SKUs where n79 is not required. Similar techniques can be used to protect cellular n79 from Wi-Fi 5 transmission.

In addition, potential application scenario exists in NR-LAN interworking in dual connectivity, which has been discussed in 3GPP as work item. Having hardware based solution will help UE take advantage of this advanced capability.

Besides antennaplexer, there's other approach to improve coexist performance by notch filter in each transmission path. Table 6-5C below shows a simplified link budget analysis indicating the out-of-band rejection requirement for 5 GHz Wi-Fi filter. Note that two TX chains are considered for 5GHz Wi-Fi system hence the allowed noise floor is 3dB less than the normal value. However a wideband bandpass filter that covers the full 5.15 - 5.85 GHz band and has approximately 40 dB rejection over 4.8 - 5.0 GHz is yet to be developed. A possible implementation at the moment is a notch filter with its main specs listed in Table 6-5C. Figure 6-30F shows the simulation results using FBAR technology.

Similarly, Table 6-5E shows the out-of-band rejection requirement for n79 filter. A possible implementation is a narrowband bandpass filter with its main specs listed in Table 6-5F and Figure 6-30G shows the simulation results using FBAR technology.

Table 6-5C Notch Filter Specs for 5 GHz Wi-Fi

Insertion Loss (Typ)	5150 - 5850 MHz	<1.5 dB



Stop Band Rejection (Typ)	4800 - 4960 MHz	42 dB
Size	1.4 mm x 1.1 mr	n x 0.4 mm MAX

Band	n79L	n79H		
Frequency (GHz)	4.4 - 4.8	4.8 - 5.0		
Noise Floor* (dBm/Hz)	-177	-177		
WiFi PA Out-of-Band Spectrum (dBm/Hz)	-125	-120		
Overall Rejection Required (dB)	52	57		
Antenna Isolation (dB)	15	15		
Out-of-Band Rejection Required for WiFi Filter (dB)	37	42		
* Considering two chains				

Table 6-5D Out-of-Band	Rejection R	Requirement [•]	for 5	GHz	Wi-Fi	Filter
	Rejection	equilement	101.5	0112		inter





(simulation data provided by HunterSun)

Band	5 GHz Wi-Fi
Frequency (GHz)	5.15 - 5.85

Table 6-5E Out-of-Band Rejection Requirement for n79 Filter



Noise Floor (dBm/Hz)	-174
N79 PA Out-of-Band Spectrum (dBm/Hz)	-120
Overall Rejection Required (dB)	54
Antenna Isolation (dB)	15
Out-of-Band Rejection Required for N79 Filter (dB)	39

Table 6-5F Narrowband Bandpass Filter Specs for n79H

Insertion Loss (Typ)	4800 - 4960 MHz	<1.5 dB
Out-of-Band Rejection (Typ)	5150 – 5850 MHz	40 dB
Size	1.4 mm x 1.1 mm x 0.4 mm MAX	



Figure 6-30G Frequency Response of a Narrowband Bandpass Filter for n79 (simulation data provided by HunterSun)

6.3 Sub-6GHz 5G Low Noise Amplifier

6.3.1 Existing Mobile Device Commercial Low Noise Amplifier

Products

Broadband LNA is a critical component in radar, communication, electronic countermeasures, telemetry and remote areas. In wireless communication, the higher data transmission speed



requires the higher of channel capacity. For RF receiver, the noise figure and linearity of LNA directly affects and decides the sensitivity and dynamic range of a RF receiver, which requires LNA's low noise to improve the sensitivity and power gain, to reduce the noise of next level circuit.

6.3.2 Sub-6GHz 5G Low Noise Amplifier Design

6.3.2.1 Design Challenges

Wideband LNA design challenges are to keep high gain, low noise finger and high IP3 in the full band.

6.3.2.2 Alternative Processes

The processes for LNA include GaAs pHEMT, SiGe HBT and CMOS. SiGe HBT and CMOS with good compatibility and low cost, GaAs pHEMT has excellent noise and gain performance. GaAs pHEMT (E-mode) has the 2-D characteristic of the heterojunction, in order to get high carrier mobility and low noise figure.

1) 0.15um E-mode GaAs pHEMT

(E-mode) 0.15 um GaAs pHEMT (E-mode) contains 17 masks and over 200 process steps. Each of these steps needs repeatable experiment, to ensure the whole process reliable and commercial

The domestic foundries are developing 6-inch 0.15 um GaAs pHEMT technology, one choice of 5G's PA. The main performances of this technology are given in table 6-6.

Item	Unit	Performance	Condition
TFR	ohm/sq	50+/-5	
Lg	um	0.150 +/- 0.02	
Rs (Epi)	ohm/sq	150 +/- 20	
Idss	mA/mm	<0.05	@Vgs=0 V Vds=1.5 V
Gm max	mS/mm	1000 +/-150	
Imax	mA/mm	420 +/- 100	@Vgs=+0.9V
Vp	V	0.3 +/- 0.15	@1mA/mm
BVgd	V	10 +/- 3	@1mA/mm
ft	GHz	110+/-25	
Psat	mW/mm	> 700 mW/mm	@29 GHz

Table 6-6 main performances of	of 6-inch 0.15 um	n GaAs pHEMT	technology
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The key parameters in table 6-6 are explained as follow:

- TFR: thin film resistor, produced by TaN.
- Lg: gate length, the smaller Lg , the higher Ft.
- Rs(Epi): epitaxy active layer resistor.



- Idss: the drain current.
- Gm_max: the maximum value of the transconductance.
- Idmax: the maximum value of the drain current.
- Vp: the gate threshold voltage. The gate voltage is larger than Vp, the transistor is switched on; the gate voltage is smaller than Vp, the transistor is switched off.
- BVgd: the drain-source breakdown voltage.
- ft: the cut off frequency.
- 2) 0.25um E-mode GaAs pHEMT

The domestic foundries have their own IP on 0.25 um GaAs pHEMT process technology, include material, device, integration, producing process, yield control, modeling and process design kit(PDK). 0.25 um GaAs pHEMT technology has been finished and reached the mean level of the industry.

0.25um GaAs pHEMT is applied for LNA and PA. And also provides E/D mode logic devices, 0.5um GaAs pHEMT (D-mode) for switch, ESD devices, resistor and capacitor.

Item	Unit	Performance	Condition
Idss	mA/mm	<0.01	@Vgs=0 V
GM_max_E	mS/mm	800±100	
I_max_E	mA/mm	500±80	@Vgs=+1.4 V
Vp_E	V	0.3±0.15	@1mA/mm
BVgd_E	V	12±4	@1mA/mm
ft_E	GHz	75±15	
Psat	mW/mm	>370	@10 GHz

Table 6-7 The main performances of the 0.25 um GaAs pHEMT technology

The key parameters in table 6-7 are explained as follow:

- Idss: the drain current.
- Gm_max_E: the maximum value of the transconductance.
- Idmax: the maximum value of the drain current.
- Vp_E: the gate threshold voltage,.
- BVgd_E: the drain-source breakdown voltage.
- ft_E: the cut off frequency.

In addition to above mentioned technologies, the existing SOI technology could also provide designers a cost-optimized platform to improve PPAC of LNA. With the help of SOI technology, LNAs can be realized in the RF front end modules of 4G and sub-6G 5G components.

6.3.2.3 Existing Sub-6 5G Low Noise Amplifier Products

LNA is integrated into module design as below to support n77 3.3 4.2 GHz.



Figure 6-31 Band n77 LNA in RF FEM

GTI

7 mmWave 5G Device RF Component

7.1 mmWave 5G Power Amplifier

RF PA plays a very important role in wireless communication system. With the development of communication technology, the requirement of RF PA is increasing, especially for broadband, high linearity and high efficiency. While amplifying the signal, PA must reduce the distortion of the signal as much as possible. Therefore, linearity is a very important index in the design of the power amplifier, and other indexes include gain, flatness, efficiency, distortion and so on. GaAs E-mode pHEMT technology inherits many advantages of D-mode pHEMT technology, and has the characteristics of single power, high span and high linearity. The current development trend of the mobile phone market has been extending the time of call and improving the function of the mobile phone so that it needs to keep enough performance to reduce the voltage. The E-mode pHEMT device has a very low switching voltage, so there is no limit on the offset margin.

1) 0.15um E-mode pHEMT

(E-mode) 0.15um GaAs pHEMT contains 17 masks and over 200 process steps. Each of these steps needs repeatable experiment, to ensure the whole process reliable and commercial

The domestic foundries are developing 6-inch 0.15 um GaAs pHEMT technology, one choice of 5G's PA. The main performances of this technology are given in table 7-1.

Item	Unit	Performance	Condition
TFR	ohm/sq	50+/-5	
Lg	um	0.150 +/- 0.02	
Rs (Epi)	ohm/sq	150 +/- 20	
Idss	mA/mm	<0.05	@Vgs=0 V Vds=1.5 V
Gm max	mS/mm	1000 +/-150	
Imax	mA/mm	420 +/- 100	@Vgs=+0.9 V
Vp	V	0.3 +/- 0.15	@1mA/mm
BVgd	V	10 +/- 3	@1mA/mm
ft	GHz	110+/-25	
Psat	mW/mm	> 700 mW/mm	@29 GHz

Table 7-1 main performances of 6-inch 0.15 um GaAs pHEMT technology

- TFR: thin film resistor, produced by TaN.
- Lg: gate length, the smaller Lg, the higher Ft.
- Rs(Epi): epitaxy active layer resistor.
- Idss: the drain current.
- Gm_max: the maximum value of the transconductance.



- Idmax: the maximum value of the drain current.
- Vp: the gate threshold voltage.the gate voltage is larger than Vp, the transistor is switched on;the gate voltage is smaller than Vp, the transistor is switched off.
- BVgd: the drain-source breakdown voltage.
- ft: the cut off frequency.

2) InP

Currently, GaAs device has dominated most of the market because of its mature technology in the microwave frequency band. However, InP device has higher breakdown voltage, higher average electron velocity, larger discontinuity in the bandgap at the interface of InAlAs/InGaAs heterojunction, higher 2DEG concentration, and higher electron mobility in channel, making it more suitable for high frequency applications.

For low voltage applications, InP HBT is expected to replace GaAs HBT. InP HBT is made of narrow bandgap material InGaAs. The bias voltage is as low as 0.5 - 0.6 V. In addition, InP HBT also exhibits better heat conduction characteristics, better heat dissipation capability (about 1.5 times of GaAs substrate) and higher peak electron velocity, allowing higher performance at lower voltages.

Although InP/InGaAs HBT with lattice matching on the InP substrate has superior high frequency and high speed characteristics, and lower turn-on voltage than GaAs HBT, it suffers from small substrate size, high cost, and fragility of the InP substrate, limiting its large-scale and low lost production. The capability to obtain high quality and large size semi-insulating InP substrate is key to lower cost. Therefore, to meet the ever increasing demand of InP devices, fundamental task is to grow high quality and large diameter InP single crystal substrate.

3) GaAs mHEMT

Benefiting from the cost, fragility and process compatibility issues of InP substrate, more and more research on GaAs mHEMT technology has been conducted. GaAs mHEMT technology is to grow a relatively thick InAlAs layer between the channel and the GaAs substrate. The composition of In changes from a certain value X to 0, so the mismatch of the lattice is alleviated. After the adding of a buffer layer with graded component, the component X of In in the channel layer can be chosen almost arbitrarily between 30%~60%, and the device performance is optimized with a great degree of freedom. mHEMT can be considered as InP HEMT technology on GaAs substrate. It shows superior performance to InP in terms of low noise, allowing GaAs to solidify its position at the low-end of millimeter wave, and further its way into the high-end territory of millimeter wave.

In 2008, 220 GHz-320 GHz mHEMT MMIC amplifier was reported using high In composition in InGaAs as channel to achieve high carrier density and mobility. Double InAlAs barrier layers and bilateral delta doping are designed to increase channel electron confinement and reduce contact resistance, and the buffer layer with linear component change is used to achieve

lattice matching. The Ft and Fmax are 515 GHz and 700 GHz, respectively, for the device with 35nm gate length and 20um gate width. The linear gain of the two stage amplifier is more than 10.5 dB in the 220 GHz-320 GHz frequency band, and the small signal gain is 13.5 dB at 330 GHz. In 2011, the device with 20nm gate length was reported, and the Ft was 660 GHz for the mHEMT with 2*10 um gate width. GaAs mHEMT has been able to work into the H band and enter the low-end of the terahertz. It has become an important component of the sub-millimeter wave application, with a cost advantage.

Chapter 4.1 data sources: Hiwafer.

7.2 mmWave 5G Filter

mmWave devices are supposed to have large-scale and high density distribution to meet the requirements of multi frequency and high frequency characteristics, which is bound to bring an explosive growth of mmWave filter.

1) SAW filter

Under the existing framework, the SAW filter is the main force of 2G, 3G and 4G communication technologies, and has the advantages of high design flexibility, good frequency selection characteristics and small size, and can adopt the same production process as the integrated circuit. The frequency characteristic of the SAW filter is closely related to the pitch of the IDT electrode. The higher the frequency, the smaller the distance between the electrodes is required. In fact, the spacing is not too small. The SAW filter drops rapidly after the frequency exceeds 2.5 GHz. Therefore, the SAW filter is mostly used below 2.5 GHz.

2) BAW filter

Beyond 2.5 GHz, BAW began to show the advantage. Compared to SAW, it is insensitive to temperature changes, with low insertion loss and high out-of-band rejection, making its share of 3G / 4G smartphones grow rapidly. However, most BAWs are used below 6 GHz and can reach a maximum of 20 GHz, which is applicable to 5 GHz systems below 6 GHz and can't be applied in the 5 GHz frequency band yet.

3) MEMS filter

Millimeter wave MEMS filter on the semiconductor substrate, the use of semiconductor manufacturing process constitutes a filter structure, with high Q and low loss characteristics, in the millimeter band has good performance. However, whether it is using gallium arsenide substrate or silicon substrate, the cost is relatively high. Under the conditions of ensuring a high degree of consistency, mass production is still more difficult.

4) Semiconductor chip filter based on MMIC process

The semiconductor chip filter based on the MMIC process can be integrated with the 5G system chip or integrated with the microwave multi-chip module. At the same time, due to the adoption of the semiconductor process, the batch consistency of the electric performance



is good, and the application is suitable for large-scale applications. Of course, due to its circuit form can only be integrated by plane, the circuit transmission waveform for the quasi-TEM wave inevitably surface waves, space radiation, dielectric and metal loss and other natural defects.

The domestic foundry has developed GaAs IPD process for the passive circuit design. The typical parameters of GaAs IPD process are given in table 7-2.

Typical parameters			
Motallavor	Metal 1:1 µm		
ivietal layer	Metal 2:2µm or 4µm		
Metal1-metal2 Via	PBO or Air-bridge		
MIM capacitance density	300pF/mm2 or other		
TaN thin film resistor	50Ω/□		
Inductor	High Q		
Background via diameter	40µm		
passivation	SiN or PBO		
Wafer thickness	100 or 75µm		

The LC low-pass filter and high-pass filter MMICs made by IPD process have covered 2 - 20 GHz in 0.5 GHz step, the typical MMIC area is 1 mm*0.75 mm*0.1 mm with a insert loss of 2dB.

Moreover, there are many customized band-pass filter products. The table 7-3 gives a typical 27.5 - 29.5 GHz high Q band-pass filter.

Table 7-3 The performances of a typical 27.5 - 29.5 GHz high Q band-pass filter

27.5 - 29.5 GHz band-pass filter
Central frequency:28.5 GHz;
Band width:2000 MHz;
Insert loss:≤ 3 dB;
In-band flatness: $\leq 1 \text{ dB}$ Fluctuation range<1 dB for any 1 GHz, and<0.5 dB for any 500
MHz;
Input/output return loss: ≥13 dB;
Out-band compression:70 dBc@<6 GHz
50 dBc@6~ - 0 GHz
35 dBc@20 - 26 GHz
30 dBc@31 - 34 GHz
37 dBc@34 - 40 GHz
30 dBc@>40 GHz
Group delay flatness: ≤5 ns@25 °C
Area:5.2 mm ×2 mm ×0.1 mm

The data in chapter 7.2 come from HiWafer

7.3 mmWave 5G Low Noise Amplifier

GaAs pHEMT has excellent noise and linearity performance. Owning to its high insulation rate, GaAs substrate leads to the improvement of chip inductor quality factor (Q), which helps to reduce the overall noise figure of the terminal. GaAs pHEMT has excellent noise and gain performance, and has not been widely used in the early years due to price. Now, with the progress of the process, GaAs pHEMT has become the mainstream for the development of LNA. For cost and performance considerations, the mainstream process is the gate length of 0.25 um. GaAs pHEMT has implemented the gate length 0.1um level. For example, the noise and gain of the PH10 process developed by UMS in Europe is 1.3 dB and 7 dB at 40 GHz. LNA developed by Qorvo in USA is 0.13 um gate long, cut-off frequency of 110 GHz with TQP13 technology, and the noise figure at X frequency band is lower than 0.5 dB.The Thirteenth and Fifty-fifth Research Institute of China Electronic Science and Technology Group and also developed 4 inch, 0.1 um gate length pHEMT technology for high performance LNA. At present, Hiwafer are also actively developing the 6 inch, 0.15 um gate length GaAs pHEMT technology, the development of single process has been completed, and it is in the stage of integration testing.

Chapter 4.4 data sources: Hiwafer

7.4 Switches for mmWave

Switches, the smallest active electronic components, play a critical role in the overall performance and effectiveness of wireless communication systems. Switches route the transmit and receive signals at different frequencies, enable monitoring and calibration and are the base component for functions such as phase shifting and step attenuation. 5G, the fifth generation wireless system, will continue this reliance on solid-state switching. But with 5G on the horizon, what are the switching requirements, and what makes a "great" 5G switch?

This chapter will explore a few basic specifications for 5G switching, discuss the use of SOI technology and showcase a few critical functions for switches in 5G communications systems.

7.4.1 What makes a 'Great' 5G Switch?

Switch performance is evaluated by a number of different specifications. In general, a "good" switch has low insertion loss, high linearity, high port-to-port isolation, high power handling and a fast switching time. In massive-MIMO architectures, each frequency bucket, sub-6 GHz and mmWave, will stress each of these parameters.

In mmWave systems, broadband frequency operation becomes increasingly important. To ease the transition to mmWave, switches must be able to support multiple bands, such as dual bands (28 GHz and 39 GHz), or even triple bands (28 GHz, 39 GHz and 66 GHz). In addition to multiple bands, each band has rigorous requirements on frequency-response variation. For example, a 28 GHz mmWave application will have a wide bandwidth, and the system gain can have a problem not meeting the flatness of the waveform over the wide bandwidth. Real wideband support implies minimum variation across the supported frequency band.

Due to the complexity of 5G system architectures, outstanding RF switch operation is critical to enabling the new generation of devices. Specifications such as insertion loss, high linearity and fast switching time are paramount to system performance.

1) Insertion Loss

Low insertion loss enables lower power amplifier drive, and thus lower energy consumption and higher output efficiency.

2) Linearity

High linearity lends itself to support higher order modulation schemes without signal degradation. One measurement of a switch's linearity is the third-order intercept point (IP3). A high IP3 means the device will add minimal distortion in the form of intermodulation and increased adjacent channel leakage ratio (ACLR) to the transferred signal, and it will be able to withstand more extreme blocker conditions.

3) Switching time

Comparing with LTE and sub-6GHz system, mmWave systems require faster switching to meet the requirements of the standard.

4) Power consumption and size

In mmWave system, the switch's size and power consumption are two other key factors in emerging massive-MIMO systems. As the name indicates, massive MIMO adds RF and antenna content to the base station. Switches must be compact and feature low-power consumption to be considered for use in massive-MIMO systems.
7.4.2 SOI Technology for 5G Switching

While many semiconductor technologies yield good active devices, very few yield good switches. Silicon on insulator (SOI) is one semiconductor technology that has demonstrated its effectiveness in switching.

CMOS is recognized for its manufacturing repeatability, which reduces end-product performance variability. SOI technology leverages the economic benefit of a mainstream complementary CMOS process to deliver a number of benefits, including manufacturability, performance and integration. In regard to switch performance, SOI technology delivers low insertion loss, high isolation and high linearity. In addition, SOI has the ability to integrate analog, digital and mixed-signal capabilities on a single chip. Integration of mm-wave PA, LNA, phase shifters and up/down mixers have also been achieved using fine geometry SOI (45 nm), making such technology a good candidate for fully integrated Transmit/Receive phase arrays for 5G NR above 24 GHz. This superior level of integration results in a smaller form factor, higher flexibility/configurability, higher reliability and better system performance.

8 Related 'Black Technologies'

8.1 Engineered Substrate

GTI

8.1.1 What is 'Engineered Substrate'?

Engineered substrate defines a material most of the time dedicated to semiconductor industry which is commonly made out of multiple materials layers. Its position in the supply chain is presented in figure below (Figure 8-1).



Figure 8-1 Engineering substrate in the supply chain, Soitec

Silicon On Insulator (SOI) is the most popular Engineered Substrate. It represents 6% of the silicon substrates industry and forecast to enjoy high growth. Compound materials market value is around 2%.



Figure 8-2 SOI substrate market in silicon substrates industry, Soitec

SOI history started 40 years ago. CMOS SOI was initially adopted in 1980's in space applications for its radiation hard properties. In 1998, IBM adopts SOI in large scale for its mainframe processors 'Power Cell' powering its Power PC, followed by Apple which did choose Motorola SOI processor for its G4 power station. Graphics processors derivatives were then designed on SOI for well known game console PS3, Wii and X-Box. At the same time, AMD did develop all its product line micro processor on SOI (Athlon, Turion, Opterion) moving SOI to high volume manufacturing using state of the art CMOS 300 mm foundries. In 2000's, Philips Semiconductors was the second major adopter of SOI for its high voltage IVN (In Vehicle Networking) transceivers. In the last ten years, more and more applications are using SOI substrate as presented in following parts.

8.1.2 Why do we need 'Engineered Substrate'?

Engineered substrates are today at the heart of the RF Front End Module. CMOS bulk is not much used till sources of lossless and source of distortions versus SOI but also limited in term of current handling, voltage handling, high temperature, reliability, ... versus GaAs, GaN, InP, SiC, Piezo materials. Future generations' phone and base stations will use even more engineered substrates moving to 5G.



Figure 8-3 Types of substrates in mobile phone, CMCC

There are two main motivations for China Mobile and end application leading companies to learn about Engineered Substrate:

 Awareness about new technologies in term of competitive advantage, supply chain. There are many players between end users and engineered substrate suppliers due to the supply chain complexity. Those players have not the expertise to give proper visibility to end users and could hide unintentionally key information or even hide engineered substrate as an option of differentiation;



Figure 8-4 Cellular device industry chain, CMCC

• Shorten time to market of new technology introduction. Sooner end user understands the value of a new technology and faster he will enable it in its application. In some case, decision can be taken to shorten supply chain by making a vertical



integration to limit the number of interfaces and then get closer to engineered substrate suppliers. Leading SmartPhone companies are moving in this direction and are making themselves some key differentiating parts of their product. As an example, the automotive industry is actively working to enable new technologies defined in reference technology roadmaps one year after its market introduction and not three years as it is today. SmartPhone industry is a benchmark for automotive industry in that respect.

• RF-SOI is today in 100% of SmartPhone with growing content at each generation whereas it wasn't even introduced in this market in 2011.



Source : Soitec estimates, Navian April 2017

Figure 8-5 RF-SOI content in Smartphone, Soitec

Looking at 5G, substrate technologies choice for RF is a key topic as presented in Skyworks reference white paper (Figure 8-6). Engineered substrates are clearly the preferred technology in most of key RF building blocks.





Figure 8-6 Product and Technology per Front-End modules range, Skyworks

For more direct customers such as foundries, fabless and IDM (Integrated Device Manufacturer), there are two main motivations to engage in engineered substrate:

- Improve Performance, Power, Area, and Cost (PPAC acronym is commonly used in the semiconductors industry). In 2010, GaAs was incumbent technology for RF antenna switch. RF-SOI enables same performance, and more than 30% cost reduction and 50% die area reduction. As consequence, RF-SOI has gradually replaced GaAs for switch in less than 5 years.
- Enable new applications. For the iPhone's 10th anniversary, Apple has started using 3D sensing and integrated near infrared (NIR) camera sensor with high-precision depth sensing. This camera sensor is the first imager to feature SOI substrate provided by SOITEC. This type of SOI technology allows having higher quantum efficiency with very low noise.

Engineered substrates are in most case significantly more expensive than raw bulk material because it requires process steps before moving to foundries and is often a major hurdle for foundries and fables to consider engineered substrate. But comparing cost between bulk material and engineered substrate doesn't make sense. The value proposition needs to be evaluated by end user in final application. For this reason, it is a major motivation for engineered substrate company to work and cooperate across supply chain.

8.1.3 Application

By changing the different specifications of the SOI wafer, multiple applications can be addressed.



Figure 8-7 Various SOI wafer specifications, Soitec

In following chapters, RF-SOI, PD-SOI and FD-SOI for RF will be presented in details. Meanwhile

SOI technologies can address other various applications:

- SmartPower SOI is typically dedicated to high voltage analog applications beyond 80 V. It is the case for In Vehicle Transceivers which are used in 50% of automotives today.
- Imager SOI was used in the 2010's for Back Side Image sensors before it was replaced by silicon bulk. Today, SOI imager sensors are considered since they can enable better dark noise performance and infrared capability (vision in low light condition).
- SOI is also the mainstream technology for silicon photonics. SOI allows to have on chip a light waveguide and active devices like modulator, couplers, etc. It is gradually replacing copper cable in data center then moving to longer distance for optical communication transceivers.

As said, applications are not limited to silicon CMOS on SOI. Compound materials, even polymer (plastics) can be used. As illustrated on Figure 8-8, World record efficiency for solar cell has been achieved by four junctions that convert full light spectrum into energy. Using same type of material, LED market can be addressed. Sensors are another wide range of applications that can be addressed.



Figure 8-8 Sate of the art for solar cell efficiency, Soitec

Applications are almost infinite for engineered substrates as long as they bring advantage on Power, Performance, Area and cost, or they enable new applications.

Availability in large volume through multiple sources is a major point to address for making a new engineered substrate successful adoption on the market. To address this properly, a global eco-system need to work together to guarantee all supply is in place. Having China Mobile in this eco-system is of great value.

8.2 Engineered Substrate: 'Anything on Anything'

Engineering substrate is a combination of multiple material stacks. In principle, anything can be stacked on anything, even on nothing. There are three main expertises that are required to build those engineered substrates: Smart Cut[™], Smart Stacking[™], Epitaxy. They are described in following sub-chapters.

Fourth expertise is in the DNA of engineered substrate engineers: material sciences. Silicon is the most well known material. Compound materials such as Gallium Arsenide (GaAs), Gallium Nitride (GaN), Indium Phosphide (InP), etc... are particularly interesting for RF and High Power applications as well as photonics and lighting. For companies willing to play in those applications, compound semiconductors expertise is also required.

Engineered substrate - stack the best of materials in one



Figure 8-9 Technologies involved in engineered substrates, Soitec

There are two other critical expertises:

- Metrology: in most cases, all materials stack properties need to be preserved and are guaranteed by specifications and hence they need to be measured. Interfaces between layers are also very critical. They have to remain without defect, in order to support mechanical and thermal budget treatment during foundry processing, wafer dicing and die packaging. Flatness of the wafer also needs to be under control for standard equipment to handle them. Specific metrologies are developed to guarantee all parameters over full wafer surface (center to edge).
- Manufacturing expertise: Engineered substrates do not behave like standard bulk wafers during processing since materials in the stack are different. They have different crystallography, different thermal expansion, etc... To move engineered substrates into final processing, foundries requires often support by engineered substrate companies to



provide them with best practice as well as metrology recipes.

8.2.1 Smart Cut™

8.2.1.1 SIMOX

SIMOX was the first SOI technology produced for thin SOI. Process was based on oxygen ion implant into silicon base wafer (Figure 8-10). After a high temperature anneal, final SOI was achieved. This technology disappeared in late 90's when Smart Cut[™] moved to production. This technology was not capable to compete in term of performance, cost and manufacturability.



Figure 8-10 SIMOX process steps, RFMD

8.2.1.2 Smart Cut™

Smart Cut[™] was invented by Michel Bruel from CEA-LETI laboratory in France. Mr Auberton Hervé and Mr Lamure created Soitec in 1992 as a spin-off from CEA-LETI. This technology is now mainstreams for thin film SOI. This technology is licensed by Soitec to Shin Etsu Handotai (SEH) and Global Wafers. All three companies deliver 99.9% of all thin film SOI.

Smart Cut[™] process starts with an oxidation of a wafer (wafer A). This oxide will be the final oxide layer of the SOI wafer. This oxide layer is called buried oxide (BOX). Then hydrogen implantation is done through the BOX and through a well determined silicon layer thickness representative of the final top silicon layer on the SOI wafer. Implanter energy is usually capable to implant through up to 1.5um. Then the implanted wafer is bonded onto a so called handle wafer (wafer B). Then splitting happens when doing a high temperature anneal that grows the hydrogen atom to create a very clean fracture that propagate across the donor wafer. Handle wafer is re-used (Refreshed) multiple times. A final finishing is done before final SOI wafer delivery.



GTI 5G Device RF Component Research Report



Figure 8-11 Smart CutTM process steps, Soitec

8.2.2 Smart Stacking™

There are cases when Smart Cut[™] is not applicable or not preferred technology. Soitec created Smart Stacking[™] using the bonding and thinning of two wafers, those wafers being potentially partially or fully processed.



Figure 8-12 Smart StackingTM process steps, Soitec

8.2.2.1 B-SOI (Bonded SOI)

This technique is used for making thick (>2um) silicon layer. This is the simplest case when two silicon wafers are bonded with an oxide. Due to thinning techniques limitations, silicon film thickness and uniformity (Flatness of the silicon film) control is one fold worse than in the case of Smart Cut[™]. When thick SOI is required with accurate thickness and uniformity, Smart Cut[™] wafers are used and then run through silicon epitaxy to increase top silicon thickness.

8.2.2.2 Thin Layer Transfer

When two different materials to be bonded have very different thermal expansion or crystallography properties, there are cases where Smart Cut[™] is not applicable as the structure may break during splitting process step. In that case, wafer A will be an SOI wafer and wafer B made from another material than silicon. As an example, Silicon on Sapphire (SOS substrate) wafers produced by Soitec and designed by Peregrine for high end antenna switch was integrated into famous Smartphones (Figure 8-13).



Figure 8-13 Bonded Silicon on Sapphire, Soitec

8.2.2.3 Circuit layer transfer

Circuit layer transfer is a more complex usage of Smart Stacking[™] technology. The target is to transfer a fully processed layer onto a base wafer, this base wafer being silicon or non silicon substrate. Processed wafers metallization cannot support in most case the thermal budget required for wafer bonding. In some cases, the base wafer is not compatible with CMOS process either for non compatibility with foundries contamination rules or thermal budget, then circuit layer transfer is also applied. In all those cases, customized bonding techniques are developed. Doing a single layer transfer, transferred circuit will be upside down. When this case is not applicable, a double layer transfer will be done. See below example of a circuit transferred on glass (Figure 8-14). An insulator such as glass is ideal for RF since it is a lossless material. Silicon RF circuit performances will be improved once transferred onto glass.

Double transfer onto an optimized support

Figure 8-14 SOI devices transferred onto 200mm fused silica wafer, Soitec



8.2.3 Epitaxy

Epitaxy is a technique to deposit molecules of a material onto a base material. Deposition can be done either by vapor deposition, beam.... Epitaxy in most case is used to stack multiple layers onto a material, this material having crystal properties close to the epitaxial layer. When materials are different, buffer epitaxial layer is required to avoid major defectivity and undesired effects. Epitaxy is a mainstream technique in compound semiconductors. As an example, GaAs transistors are built from a bulk GaAs wafer that has been grown by an Epi vendor before going into the foundry for lithography.



Figure 8-15 Molecular Beam Epitaxy Flow example, Soitec

8.3 CMOS on SOI

As mentioned in introduction, since 40 years, CMOS industry has been using CMOS SOI. The following subchapters develop the different SOI CMOS technologies with focus on RF and mixed signal applications. The Figure 8-16 illustrates the overview of SOI technologies in GlobalFoundries lithography nodes.

←		200mm						300mm			
	0.5µm	0.25µm	0.18µm	0.13µm	90nm	65nm	45nm	32nm	22nm	14nm	7nm
Patterning Performance & area	KrF 248nm				ArF 193nm			ArF immersion		2xPatt	3xPatt EUV
Thermal Junct Eng. & Activation					spike		msec anneal				
Etch Device architectures					St Dim	top on sili nension o	icon ontrol				
Epitaxy Device architectures						SiGe S/D	SiCP S/D		SiGe c	hannel	
Materials Device architectures Low resistance Gate stack Wafer type	PtSi	CoSi	PDSOI SOI	HR/TR SOI		NiSi	Strain	FinFET High K	FDSOI		

Figure 8-16 Process and materials overview of GlobalFoundries CMOS SOI technologies, Global Foundries

8.3.1 CMOS on SOI basics

CMOS on SOI have each NMOS and PMOS transistor fully isolated by an oxide wall whereas on bulk, NMOS and PMOS transistor are isolated by reverse PN or NP junctions. As a consequence, as a rule of thumb, stray capacitances on SOI versus bulk are divided by 10 (Figure 8-17 (1)).

The following sub chapters develop the impact for RF and mixed signal circuits. We commonly admit that digital circuits on SOI run over 30% faster than on bulk or consume over 30% less than bulk using same lithography node. We can also consider that CMOS on SOI allows the use of one older lithography generation and get same performance as the newer one. In the 2010's, AMD microprocessors were having same performance as Intel's even Intel was using one generation of CMOS node ahead of AMD.



Figure 8-17 (1) Intrinsic MOSFETs parasitic capacitances bulk versus SOI, UCL





Figure 8-17 (2) Transmission Electron Microscopy (TEM) cross section bulk versus SOI, STM

8.3.2 Basic SOI Advantages

8.3.2.1 Low Power

SOI technology is ideal for Low Power CMOS applications. On top of digital active low power performances mentioned in introduction (over 30% better than bulk CMOS is same conditions), SOI digital circuits also benefit when in inactive mode or sleep mode since there is no leakage current through junction to substrate. Last but not least, CMOS SOI transistor can run at extreme low voltage thanks to its well controlled channel electrostatic and low threshold voltage variation. Library running down to 0.4 V are now available.

Below graph represents the power saving in different market segments versus silicon bulk. Improvement is up to 1000% for ultra low power applications. Even further improvement is achieved when applying body back-bias (BB).



Figure 8-18 Power saving FDSOI versus bulk in different market segments, Soitec

8.3.2.2 Better Isolation - no Latch-Up

1) Isolation: transistors on SOI are isolated by oxide capacitances which are 10 times lower



than junction capacitance on bulk. Default, isolation performance are at least 20dB better on SOI. System integration is an historical trend in microelectronic. Combining sensitive small signal circuits like receivers with high voltage high power circuits such as power amplifier and digital processing will benefit of SOI isolation. Combining very different supply domain on single die is not a concern on SOI whereas it requires specific design rules and extra deep isolation trench on bulk.

2) Latch-Up: For critical analog circuits having high voltage pulse than can create peak voltage below ground, current is injected into the substrate and can enable a latch-up effect. Latch-up happens when a bipolar structure made with NMOS and PMOS wells which is normally OFF gets ON and short-circuits the transistors making the circuit malfunctioning. Latch-up can happen in CMOS System-On-Chip integrating a RF power amplifier if design margin are not sufficient. Latch-up cannot happen on SOI since this well structure does not exist. For application requiring positive and negative voltage, CMOS on SOI is the preferred technology. As shown in figure 8-19, Latch-up will not happen on SOI.



Figure 8-19, Latch-up will not happen on SOI

8.3.2.3 Hard Radiation tolerant

Historically, SOI first application was in space electronics. SOI is by default space particles tolerant since those particles mainly go through the BOX and do not interact with the active layer. Soft error rate in SOI are few fold better than on bulk. Current satellite constellation programs like SpaceX should take advantage of SOI. Beyond space applications, aeronautics and automotive electromagnetic sensitive circuits take advantage of SOI.

8.3.2.4 High temperature operation

Junction leakage current increases exponentially with temperature. It makes bulk circuit not functional and reliable in most case above 125 degree Celsius whereas they are till 250 degree Celsius or more on SOI. It makes SOI the technology of reference for harsh condition electronics like mining, space, aeronautics, automotive....

8.3.3 PD-SOI and FD-SOI – Definition

FD (Fully Depleted) and PD (Partially Depleted) SOI is often a subject of confusion because there are two levels of definition: technical and market definitions. A previous article has been published in 2015 on this topic. The reference link is :

https://soiconsortium.eu/2015/10/28/rf-soi-vs-fd-soi-with-rf-whats-the-differenceTechnical Definition

8.3.3.1 Technical Definition

The drawing below (Figure 8-19A) simply shows the difference. The channel in one case is completely depleted (fully depleted) and is not in the partially depleted case. Deep physics understanding and electrostatics equations are required to go beyond this simple definition. To make channel fully depleted, a certain gate voltage over silicon thickness ratio is required. It explains why in most cases fully depleted mode is achieved using a silicon layer thickness much smaller than on partially depleted. Since channel tends to be symmetrical in fully depleted mode, an ultra thin BOX (~ 20 nm) can be used as a second transistor gate. It is the so-called back-bias FD-SOI feature. Lithography node does not define if the technology is fully depleted or not.





8.3.3.2 Market Definition

RF-SOI targets Front End Module application mainly today including transceiver when moving to 5G mmWave. The lithography is typically 130 nm in 200 mm, moving now to 90 nm and down to 45 nm on 300 mm in present new RF-SOI generations. In following chapter on RF-SOI, we will see that both partially and fully depleted transistors are used.

PD-SOI mainly target either legacy digital microprocessors and ASICs circuits. FD-SOI target System-On-Chip highly digital and mixed signal ICs. As for RF-SOI, digital transistor can also be used either in partially or fully depleted mode. By the way, during the last five years, the roadmaps have all moved to fully depleted, partially depleted being in most cases a legacy process.

To avoid confusion, when talking about PD-SOI or FD-SOI, it is important to make sure what

topic is addressed: technical or market.

8.3.4 Floating body and Body contact

In case of PD-SOI, in normal operation, $V_B \sim V_S$ as in bulk CMOS. Body is floating. It is called 'floating body'. When going far in saturation, impact ionization creates holes current in NMOS, making $V_B > V_S$ which makes transistor threshold voltage drop and then increases drain source current. It is called the Kink Effect.

Kink effect by definition happens in digital circuit and boost speed performance. In analog, this non linear effect is often non desirable and designer will design under V_{DS} < $\sim 0.6V$ (Figure 8-20).



Figure 8-20 Kink effect, UCL

An alternative is to contact the body to keep its voltage constant. It is called 'body contact'. In certain case like on RF-SOI antenna switch, body is put under ground, typically 2.5 V, to further reverse the junction capacitance and then reducing their value and non linearity effect. In case of FD-SOI, there is no Kink Effect (Figure 8-21). Body contact can be still used to improve linearity for example in case of RF-SOI antenna switch.



Figure 8-21 Kink effect bulk, PD-SOI and FD-SOI, UCL

8.4 CMOS on SOI for RF

Purpose of this chapter is to review the SOI technologies and value for RF, from 4G Front End Modules to 5G, transceivers and beyond.

8.4.1 RF-SOI

RF-SOI targets Front End Module application building blocks: switch, tuner, power amplifiers, low noise amplifiers, passives. Simple definition of RF-SOI could be silicon CMOS compatible layer on quasi lossless substrate.

Performances can be limited by design, back-end of line process (also named metallization), Front-End of line (also name diffusion) and substrate (Figure 8-22). RF-SOI substrate target is to not be a limiting RF performance factor, ideally be a quasi lossless substrate with a high thermal conductivity enabling lower application cost and smaller footprint.



Figure 8-22 RF-SOI process cross section, UCL

RF-SOI has already 25 years of history (Figure 8-23). HR-SOI and Trap Rich RFeSI[™] are the key inventions that make this technology mainstream for switch and tuner with 90% market share according to market analyst Navian. Thanks to its present move to 300 mm with 90 nm node and below available, Low Noise Amplifier with switch on chip is also massively moving to SOI. Power amplifier has some limited market penetration on Wifi and cellular market versus GaAs due to mainly lower power efficiency.





Figure 8-23 History of RF SOI, Soitec

8.4.1.1 HRSOI

HR-SOI (Figure 8-24) is made with Smart Cut[™] on high resistive handle substrate (> 1kΩ.cm).



Figure 8-24 HR-SOI process, Soitec

Despite using high handle substrate resistivity before SmartCut^M, the HR-SOI effective resistivity under AC signal falls down to around 100 Ω .cm. BOX is done with silicon oxide. Although an insulator, this oxide is positively charged. In response to these charges, a 'parasitic surface conduction' (PSC) layer is formed under the BOX. This conductive layer (Figure 8-25) highly degrades the expected RF performances (insertion loss, linearity, isolation) but still remains better than bulk.



Figure 8-25 Parasitic conductive layer on HR-SOI process, Soitec

8.4.1.2 Trap Rich SOI - RFeSI™

To avoid this parasitic surface conduction, two techniques were invented:

1) HSP (Harmonic Suppression Process) developed by IBM (now Global Foundries) using lithography.

First, the process etches vias through the BOX, then implants heavy ion to damage the silicon surface below the BOX and refills the via with oxide. The damaged silicon area has traps that significantly reduce charge mobility. Beside is also added a contact (poly contact) to bias the region around the heavy ion implant to further reduce the parasitic surface conduction effect. This technique cannot be used under transistors. Transistor process needs to be done before since a high temperature process would cure the damage done by the implant. This technology requires a thick BOX (>1um).



Figure 8-26 Cross section of HSP process, IBM (now Global Foundries)

2) Trap Rich layer developed by Soitec and UCL.

This layer is done before the Smart Cut[™] bonding process. The trap rich layer is spread across

the entire wafer whereas it is only under passives with HSP techniques. Charge mobility under the BOX is highly reduced by this high density traps layer. BOX as thin as 200 nm can be used without impacting performances. It enables easier wafer process at both engineering substrate and foundry side, improving throughput, yield and cost of the manufactured devices. Soitec branded this technology RFeSI[™] (RF enhanced Signal Integrity).



Figure 8-27 Parasitic conductive layer on HR-SOI process, Soitec

Both technologies moved initially in volume production. Most foundries latest generation processes are now using RFeSI[™].

RFeSITM improves all critical parameters required for RF Front End Module devices. Effective resistivity of the last generation RFeSITM is above $8k\Omega$.cm and measured performances are getting close to an insulator such as quartz. Further improvements are still expected on linearity and insertion loss in order to meet the most stringent cases supporting dual transmission either for carrier aggregation or dual 4G and 5G connectivity cases. Although performance limitation may mainly comes from transistors.



[K. Ben Ali, J.-P. Raskin, SOI'12, IEEE TED'14]

Figure 8-28 Electrical characteristics on HR-SOI, Trap Rich SOI and Quartz substrates, UCL

In term of RF-SOI roadmap, the trend is to move to fully depleted to improve switch Ron*Coff figure of merit. Fully depleted transistors have less stray capacitance thanks to thinner film. Ron*Coff has been reduced from over 350 fs to around 100 fs and more reduction are expected while keeping breakdown voltage constant.



Figure 8-29 Ron*Coff trend versus substrate type, Skyworks

8.4.1.3 RF-SOI for Switch, Tuner, LNA, PA

1) RF-SOI for Switch and Tuner

From an RF-SOI substrate perspective, 90% of switch and tuners are built on RF-SOI as illustrated on Figure 8-30.



Figure 8-30 Main RF Front-End modules market, Navian Report 2016

RF-SOI has all key merits to remain the mainstream technology for switch. It is by far the best tradeoff between performance (meet LTE A PRO specifications), price (Bulk only is cheaper), area (more and more analog integration (LNA, Tuner, passives ...) with digital (MIPI bus, control logic ...)). MEMs have been perceived for years as a potential player for high end devices. Due to its high cost, higher area, low reliability, it remains a challenger.

2) RF-SOI for LNA

For most advanced carrier aggregation case and MIMO, LNA is becoming a key function. RF-SOI presents three key advantages.

- Inductor high quality factor (see next on PA)
- Access to 300 mm and lithography equal or below 90 nm
- Integration with switch

Most recent data show that LNAs on RF-SOI are equivalent to SiGe which cannot compete in integration as it enables poor switch performance.



Figure 8-31 LNA + SWITCH in advanced FEM architectures, Soitec

Power Amplifier remains the last devices in the RF Front End Module to broadly adopt RF-SOI.

3) RF-SOI for PA

Power Amplifiers on RF-SOI have major advantages versus bulk:

• Inductors quality factor improvement on RFeSI™



2 nH spiral inductor integrated on top of HR SOI and TR SOI substrates – Cu wire of 35 μm -thick.



145nm

Buried Oxide

A-A

Figure 8-32 Inductor quality factor HR-SOI versus Trap Rich SOI, UCL

Transistor stacking enabling voltage handling beyond single transistor breakdown voltage



Figure 8-33 Stacked MOSFET Power Amplifier, UCSD

- Specific extended drain devices developed by foundries with high BV * Fmax product contact Drain Drift Body conta DP 70n STI ity handling substrate

O. Bon et al, "RF Power NLDMOS Technology Transfer Strategy from the 130nm to the 65nm node on thin SOI", IEEE Int. SOI Conf. 2007

Buried Oxide B-B'

Figure 8-34 RF power NLDMOS on SOI, STM





Figure 8-35 Electrical characteristics on SOI, STM

RF-SOI PA is tunable and its embedded digital CMOS can be used for tuning at specific band. Owing to the power density and mobility, the PAE performance of GaAs is so well has to the main material used for 4G components. While RF-SOI is mainly used towards middle and lowend smartphone market. In order to expanding the application of RF-SOI for PA, the foundries and fabless semiconductor companies take great efforts in developing RF-SOI.

As shown in follow figure, RF-SOI is a unique platform which can be fully integrated, and it is a alternative choice when needed.



Figure 8-36, Soitec

8.4.1.4 RF-SOI eco-system

A technology needs a strong eco-system to become mainstream. All leading foundries have strong roadmaps to further develop RF-SOI, in both 200 mm and 300 mm. According to Soitec estimates, worldwide RF-SOI production in 2018 was 1.45 million wafers 200 mm equivalent moving to 2 millions beyond 2020.

GTI



Figure 8-37 RF-SOI industry ecosystem, Soitec

8.4.2 PD-SOI for RF is now called RF-SOI

When talking about PD-SOI for RF, target market is mainly related to microwave to mm wave circuits. As mentioned in the introduction, SOI was mainly used for digital applications like AMD microprocessor, game console, ASICs till around 2010. Those applications did follow Moore's low down to 45 nm. IBM now Global Foundries has developed a complete new RF back end and analog options to adress mmW applications like Low Earth Orbite transceivers, 5G, Automotive radar, etc... A specific SOI substrate was designed re-using same options used in RF-SOI: high resistivity substrate and trap rich layer.

This technology offers un-matched performance with NMOS Ft/Fmax > 300 GHz and PMOS Ft/Fmax > 250 GHz (Figure 8-38).







Figure 8-38 Ft/Fmax electrical characteristics on PD-SOI technology, Global Foundries

This technology has been available during around 5 years. University and academics have largely published on all building blocks required for mmWave radio: ADC, DAC, mixers, VCO, PLL, phase shifters, couplers, LNA, PA.

This technology is well positioned for mmWave full radio implementation, particularly when using a heterodyne architecture (Figure 8-39). For mmWave, it is important to have the antenna and the mmWave radio devices as close as possible to avoid any path and package losses as well as high power added efficiency (PAE)..





Skyworks demonstrates 45 nm RF-SOI capability for mmWave radio devices as illustrated on Figure 8-40 below. Design can be fine tune to achieve best PAE typically above 25% at target system output power. Output power up to 23 dBm is achievable.

	ISSCC '16	ISSCC '15	ISSCC '14	JSSC '13	SiRF '14	SWKS '17
Technology	28 nm CMOS	28 nm FD-SOI	40 nm CMOS	40 nm CMOS	120 nm SiGe	45 nm SOI
Frequency	28	60	60	60	28	28
Supply (V)	1	1	2x 0.9	1	3.6	4.8
# of Stages/PAs	2/1	3/4	3/2	3/2	1/1	1/1
Gain (dB)	15.7	15.4	22.4	17	15.3	21
P _{sat} (dBm)	14	18.8	16.4	17	15.3	21.5
P _{1dB} (dBm)	13.2	18.2	13.9	13.8	15.5	19.5
PAE _{max} (%)	35.5	21	23	30.3	35.3	32
PAE _{1dB} (%)	34.3	21	18.9	21.6	31.5	26
PAE _{psat -9.6 dB}	10	7	5	6.5	10.5	9

Figure 8-40 45 nm RF-SOI mmWave Power Amplifier design (not optimized design, trade off linearity / PAE), Skyworks

To not confuse SOI users, PD-SOI is now called RF-SOI whatever the node is when done on high resistive substrate handle.

8.4.3 FD-SOI

8.4.3.1 FD-SOI wafer capability

For 28 nm lithography and beyond, the FD-SOI technology that has been developed is called UTBB, standing for Ultra Thin Body and Box. Body stand for the silicon layer typically around 10 nm. Box is around 20 nm.

UTBB-FDSOI

- FDSOI = <u>Fully Depleted SOI</u>.
- UTBB = <u>U</u>ltra <u>Thin B</u>ody & <u>B</u>OX



At 28nm node and beyond



Source: STM, 2012

Figure 8-41 UTBB-FD-SOI technology, Soitec and STM

In fully depleted mode, transistor threshold voltage is dependent of the silicon layer thickness. During many years, the eco-system didn't engage into this technology fearing that meeting silicon uniformity specification would not be feasible as Moore's Law continues. Volume production having uniformity capability of +/-5 Å wafer to wafer has been realized, all wafer (Figure 8-42). This uniformity is equivalent to few atoms of silicon. Research laboratory CEA-LETI did demonstrate FD-SOI transistors at 7nm lithography.



Silicon thickness uniformity is guaranteed to within just a few atomic layers: Top Si uniformity = +/-5 Å at all points on all wafers, equivalent to +/- 1.5cm over Paris-Chengdu



Figure 8-42 FD-SOI Silicon thickness uniformity, Soitec

8.4.3.2 Back-Bias

FD-SOI UTBB wafers are designed with ultra thin Box to enable back-bias. Box is used as a second transistor gate. It enables Vt modulation. Such a technique is also use in Bulk CMOS but Vt tuning capability is 10 times lower (Figure 8-43).





Figure 8-43 Forward and reverse back-bias in FD-SOI

In digital applications, transistor can be put in ultra low leakage current mode when idle or in high performance mode when maximum operating frequency is required (Figure 8-44).



Figure 8-44 Frequency/power flexibility 22 nm FD-SOI, Global Foundries

Back-bias is also used to compensate process variation improving circuit yield, performance spread, minimum operating voltage, etc..., as presented below.



Figure 8-45 Design compensation with FD-SOI, Soitec

As an example, see trimming results on a 60 mm² 28 nm processor circuit today in volume production.





Figure 8-46 Trend Leakage/Operating frequency with FD-SOI, Soitec

In analog, back-bias technique opens the door to new circuit topology since two gates with two different transconductances are available.

8.4.3.3 FD-SOI for analog

As mentioned in the previous chapter, we can take advantages of FD-SOI material with backbias control for digital applications. Meanwhile, FD-SOI can also be used and valued compared to bulk. The active device benefits for analog applications are the following:

 Mismatch reduction due to undoped channel and no halo implants compared to bulk (>30%)

A∆vtsat (mV-μm)					σ(∆vtsat) (mV)				
	40LP	22fdx	Diff			40LP	22fdx	Diff	
N	4.45	1.65	-63%]	Ν	42	23.6	-44%	
Р	2.89	1.61	-44%]	Р	28	23.1	-18%	
A∆idsat (%-µm)					σ(∆idsat)/idsat (%)				
	40LP	22fdx	Diff			40LP	22fdx	Diff	
Ν	0.94	0.47	-50%		Ν	9.2	6.16	-33%	
Р	0.77	0.49	-36%		Р	7.5	6.87	-8%	

Figure 8-47 Vth and Idsat mismatch 22 nm FD-SOI versus bulk, GlobalFoundries

- Higher intrinsic voltage gain than bulk gm/gds (Figure 8-48)
- Higher gm/Ids (Figure 8-48)
- Lower gds (as much as 1.8X on bias) than bulk
- Lower parasitic capacitance





Issues for back bias to address analog design are illustrated with Figure 8-49 and Figure 8-50.

Moreover back bias techniques should allow performances trimming: Gain, Bandwidth, Delay ...



Figure 8-49 Amplifier bandwidth improvement in 22 nm FD-SOI, Global Foundries

The second se		
Device Parameters	Circuit Benefits	Example Circuits in Typical Analog SoC
IDSat/Ion/Ioff	Dynamically adjusting logic time delay, rise/fall time, clock speed, area Dynamically power vs. performance tradeoff	Digital logic and signal processing Clock and LO buffer Ring Oscillator Time-to-digital converter (TDC) Delay line Inverter based –gm for VCO and DCO
RON/ROFF	Switch with low ON resistance and high OFF resistance ratio	Programmable capacitor such as C-DAC Programmable DCO capacitor array Programmable resistor such as R-String-DAC and R2R-DAC Switched-capacitor sampling network for ADC Switched-capacitor filter Switched-capacitor charge-pump generator Passive mixer Chopper stabilization circuit Switched-subilization circuit Switched-subilization circuit Switched-subilization circuit Switched-subilization circuit Switched-subilization circuit Switched-subilization circuit Switched-subilization circuit Switches and analog muxes RF Front-end Switch
DC operating point adjustment	Optimizing headroom Common-Mode	Linear regulator Amplifier Comparator Current mirror/source/sink
GM/GM-C	Calibration and tuning	Inverter-based gm/C filter Inverter-based gm/C sigma-delta modulator
Mismatch	Offset correction	Comparator and amplifier Mixer and amplifier HD2

Application Categories



For lithography below 22 nm, the CMOS roadmap has moved to FinFET. FinFET is a 3D CMOS structure using thin (Figure 8-51). Gate is around a fin, allowing better electrostatic control whereas it wasn't possible anymore on planar CMOS.



Figure 8-51 FinFET architecture

When comparing FD-SOI UTBB against FinFET without strain, the transistor gain remains larger, even more when going to narrow channel. Due to lithography constraint, the fin height and width are fixed which means that designers are losing significant flexibility for design.



Figure 8-52 Gain MOSFET transistor FD-SOI versus FinFET, SSE 2012

More important, FinFET process is significantly more complex and expensive than SOI CMOS and also requires more design resources.

8.4.3.4 FD-SOI for System-On-Chip Wireless IC

Based on performance and cost data presented, FD-SOI is the ideal platform for highly integrated mixed signal system like transceivers integrated with Modem and MCU.

As an example, Sony has launched on the market a fully integrated GPS circuit (receiver + demodulator + signal processing) claiming that it consumes 5 times less current than the competition. This circuit is used in Xiaomi SmartWatch and almost all other Tier #1 Sporrt watches brand.



Figure 8-54 Sony GPS circuit in FD-SOI, Global Foundries
8.4.3.5 FD-SOI for mmWave

FD-SOI is the logical roadmap following planar CMOS bulk for mmWave. FinFET cannot be effectively used for mmWave due to its 3D structure and then large stray capacitance. Ft/Fmax of FinFet is around half of FD-SOI at same node.



Figure 8-55 MOSFET Cutoff frequency FinFET versus planarFET

Whereas FD-SOI is primary targetting advanced digital signal processing with transceivers, it keeps intrinsic capabilities of SOI for power amplifiers and switch with reduced output power capability compared to RF-SOI 65 nm (< 20 dBm). In case of complex phase array where single power amplifier output power remains below 20 dBm, FD-SOI allows a full 5G system integration from antenna to digital baseband and application processor using direct conversion architecture (Figure 8-56).



Figure 8-56 FD-SOI for 5G mmWave Front-End Module, Global Foundries

Using back-bias, some novel architecture can be designed. As an example, the use of back-bias allows to revisit classical PA architecture (Figure 8-57). The contribution of wide range FBB bias drives to have a gradually change the overall class of Power Amplifier. In the same time, efficiency and linearity was optimized.





Figure 8-57 mmW Power Amplifier using back bias in FD-SOI

As of today, FD-SOI has no high resistive bulk options.

8.4.3.6 FD-SOI eco-system

A technology needs a strong eco-system to become mainstream. In early 2010s, ST Microelectronics and ST-Ericsson were the first to develop and ship for cellular microprocessors on FD-SOI at 28 nm. On dual cortex A9 running at 1.85 GHz, they demonstrated FD-SOI 28 nm was outperforming versus 28 nm Bulk (Figure 8-58).



Figure 8-58 cellular microprocessors power saving FD-SOI versus bulk, STM

In 2017, FD-SOI eco-system is in place with process offering from 65 nm down to 12 nm from four different foundries as well as IP and design services. (figure 8-59).

GTI





Figure 8-59 FD-SOI ecosystem, Soitec

8.5 Non Silicon Engineered Substrate

8.5.1 Non Silicon materials for RF

Silicon (bulk and SOI) is today mainstream in semiconductors industry with 98% of volume. It doesn't mean that non silicon materials are not of interest. As presented in this chapter introduction, when state of the art performances are required like in Front End Module, silicon is not dominant anymore.

Ideal characteristics of RF materials are:

• Loss less: high resistivity, low permittivity

High resistivity means above 10 k $\Omega.cm:$ it is at the limit of silicon capability. Low



permittivity means by definition below silicon ($\varepsilon < 11.3$). As an example, glass and ceramic are ideal. They are used for high end passive device, printed board circuit.



Figure 8-60 Sate of the Art materials electrical resistivity and thermal conductivity, Soitec

• High frequency capable: high electron and hole mobility High mobility means above 3000 cm2 V-1 s-1 for electron. Compound semiconductors are ideal, especially because mobility is not so much degraded under high current density. It makes GaAs an ideal substrate for cellular power amplifiers.



Figure 8-61 Sate of the Art materials' mobility, UCL

• High power and high voltage: high bandgap voltage and thermal resistance

Silicon has 1.22 V bandgap voltage. High bandgap material has >3 V. For example: GaN, Silicon Carbine, Aluminum nitride, Diamond.

Silicon has thermal resistance of 148 W.m⁻¹·K⁻¹. Silicon Carbide and Diamond are much higher. Heat dissipation can be improved with proper packaging. For example, GaN has not state of the art properties whereas it is reference material for power.



Figure 8-62 Sate of the Art materials' bandgap

In theory, there would be an infinite number of offers for engineered substrate materials to address dedicated RF applications. In practice, a strong eco-system is required in order to move new material into high volume production. Most of the time, integrated device manufacturers (IDM) are addressing those markets by developing their own IP and expertise on substrate, process and circuit design. As an example, Wolfspeed with CREE has developed a fully integrated supply chain from silicon carbide wafering to gallium nitride circuits (GaN on SiC) product lines. Part of the GaN market is then captive. This situation could slow down market growth of GaN in 5G base station that we see today. According to Mobile Expert, 30% of base station PA are using GaN on SiC. GaN on SiC PA have better performance than LDMOS PA for frequency above 2.5 GHz and power above 30 dBm. GaN on Silicon is an alternative solution that has been developed and pushed for its optimum performance at cost in between LDMOS and GaN/SiC. Most of GaN on silicon players are also developing proprietary process from wafers to end products. It limits then the development of pure play foundries offering and global eco-system serving high volume at competing cost. Except for Gallium Arsenide (GaAs), there is no real global eco-system on any other non silicon engineering substrate materials today. As a result, only GaAs ecosystem has pure foundries like Win Semiconductors, AWSC, new entrant like HiWafer and Sanan serving or on top of incumbent leaders like Skyworks, Qorvo, Broadcom.

Nevertheless beyond GaAs and driven by 5G, this chapter of non silicon material for RF has been further developed as we foresee major opportunities and further growth in particularly for GaN and Piezo on Insulator (POI) for both handset and base stations.

8.5.2 Example 1: Indium Phosphide on Gallium Arsenide

In 5G mmW front end module roadmap, Indium Phosphide (InP) is often presented as the best material for power amplifier. As for 4G and 5G sub 6GHz front end module, it is interesting to note that standard silicon CMOS bulk is not seen as a process of choice.

The reason InP is the best material for 5G mmWave power amplifier is that it has best Fmax* Breakdown voltage product figure of merit (FoM)(Figure 8-63). As presented in below figures, InP FoM outperforms GaAs and SiGe by 10x. State of the art one watt power amplifiers are today produced using InP bulk material (Figure 8-64).



Figure 8-63 InP FoM, Skyworks



Figure 8-64 Power of PAs state of the arts

InP remains today dedicated to professional market. Main reason is that InP material supply doesn't really exists. It is mainly available in 100 mm size at extremely high price compared to 150 mm GaAs wafer. For InP to become mainstream in 5G base station and handset, it is then a must to have it available at competing price and in 150 mm size. Using Smart Cut[™], a new structure has been proposed: InP On GaAs (InPOGaAs). This structure removes all roadblocks of current InP to become mainstream. Affordable cost by re-using multiple time InP expensive bulk wafer, allows high volume manufacturing but also have low brittleness equivalent to GaAs and no InP waste. InPOGaAs wafers are fully compatible with GaAs epitaxy and process lines.



Figure 8-65 Why InP on GaAs, Soitec

InPOGaAs wafers prototypes were built and an epitaxy was performed. It shows excellent first time right DC transistors characteristics. As well as for bulk InP a strong engagement of key players is now required to move InPOGaAs as a mainstream process.



InP On GaAs

InP for refresh

Figure 8-66 Soitec wafer prototypes InP On GaAs

8.5.3 Example 2: Piezo on Insulator

In handset front end module, filters content is dominating (Figure 8-67).





Figure 8-67 RF Front-End modules market, Yole

Filters are done with piezoelectric materials. Piezo materials allow exchange of electrical energy into mechanical energy and vis-versa. Filter market is the biggest in the MEMs market segment. There are two kinds of filter structures. Surface acoustic wave (SAW) filters and bulk acoustic wave (BAW) filters. In SAW, acoustic wave propagates on the surface of the material. Filter frequency is defined by the interdigital transducers (IDT) made with simple metal deposition. In BAW filters, acoustic wave propagate in the volume of the material. It is made of a piezoelectric material layer inserted between two metal layers. BAW structure is either above a cavity (FBAR – invented by Avago/Broadcom), or above a Bragg mirror (Figure 8-68).





Figure 8-68 SAW versus BAW Technology comparison, Triquint (now Qorvo)

SAW filters address low – mid band and BAW addresses mid-high band frequencies (Figure 8-69). The temperature stability specifications of the filters are stringent in full duplex mode especially when guard band between Rx and Tx is limited or when other band are close by. If the specification of the temperature drift is below 20 ppm/°C, the filters are said 'temperature compensated'. In extreme case, the requirement is to have a 'zero drift' frequency over the temperature range.



Figure 8-69 Type of filters versus Area Newtork bands, Qorvo

Piezo On Insulator (POI) defines a piezoelectric material on an insulator (Figure 8-70). For more than twenty years, theory has showed that new acoustic filters can be made using thin piezoelectric layers.





Using Smart Cut[™] and Smart Stacking[™] technologies, complex engineered substrates for filters can be designed. POI filters offers major advantages (Figure 871) :

• Multiple frequencies on same die for highly integrated multiplexers



- High Q for large 5G bands filters
- Embedded low temperature coefficient 'TCF' (the silicon and oxide temperature coefficient are opposite to piezo layer)
- Scalable to frequency up to 5 GHz and may be more
- POI wafer scalable to 200 mm allowing a cost down roadmap today mainstream SAW filters are done on 100 mm moving now to 150 mm.

POI looks to be the ideal substrate to address 5G well positioned in between the low cost bulk SAW filters and high end BAW filters. POI is just at the beginning of its market adoption. We foresee a global eco-system moving to this technology.

	SAW	TC-SAW	BAW	POI SAW	
	ANA A	THE CONTRACT			
Multi frequencies integration	Difficult	Difficult	Very difficult	Easier	
Q	1500	<1500	4000	4000	
TCF (ppm.k-1)	>40 (LiTaO3)	<20 (LiTaO3)	>20	<5 (LiTaO3)	
Freq (Ghz)	< 3.5	<3.5	<10	<5	
Kt ²	<7% (LiTaO3)	<7% (LiTaO3)	<10% (ALN)	<12% (LiTaO3)	
Photo complexity	Mid	Mid	Low	Mid	
Process complexity	Low	Mid	High	Low	
Substrate complexity	Low	Low	Low	High	



8.5.4 Example 3: Gallium Nitride (GaN)

As shown in tabular of Figure 8-72 and as mentioned before, GaN is the state of the art material for PA above 2.5 GHz and 30 dBm output power. GaN has the best power amplifier figure of merit for 5G <6 GHz base station power amplifier. To enable high power thermal dissipation of such PA, GaN layer is epitaxy onto a silicon carbide (SiC) wafer. True disadvantage of this solution is cost. It is the main reason silicon LDMOS remain dominant for base station today.



GaN – state of the art material for Power Amplifier

Property	Si	GaAs	SiC	GaN	2-6 GHz PAs
Breakdown Electric field (V/cm)	3.10 ⁵	4-5.10 ⁵	2-4.10 ⁵	4.10 ⁶	70
Power FOM ($\mu_n * E_c^3$)	1	20	675	3000	
Johson FOM (Ec*Vsat)/2.п	1	2.7	20	27.5	2 50 2 4 2 4 2 4 2 4 2 4 2 4 2 4 2 4 2 4 2 4
Thermal <u>Conductivity</u> (W/cm C)	1.5	0.5	3.7	1.3	30
Power <u>density</u> (W/mm)	0.8	1-1.5	4	7	0





Main reason of GaN on SiC high cost is Silicon Carbide itself. Silicon Carbide growth is very slow and limited. Silicon ingot enable forty times more wafer as compared to SiC. SiC is basically 30 years behind silicon bulk with respect to wafer diameter and crystal quality. Presently silicon carbide investment are driven by electrical cars traction inverter (electrical motor). Eco-system is growing rapidly. Analysts estimate that Silicon Carbide volume production will be multiplied by 10 in the next three to five years. Even all those investments are for electrical vehicle for different type of silicon Carbide, RF should benefit of it. A real alternative is to replace Silicon Carbide by silicon bulk ! (figure 8-73)

GaN on SiC (GaN/SiC) vs GaN On Si (GaN/Si) material perspective



Figure 8-73 GAN on SiC versus GaN on Si, Soitec

GaN on Silicon technologies are now getting to maturity driven by both power supply and RF power amplifier markets. Most of the epitaxy growth challenges are under control and wafer diameter is available in 200mm. It makes this technology very competitive with GaN on SiC. Market leaders have announced some market traction. More surprising, at MWC Barcelona 2019, MACOM and ST Microelectonics have announced GaN on Silicon for both base station and handset. GaN is considered as a >30 dBm differentiated technology so default not addressing the handset.

8.6 Conslusion

As a conclusion, in the front end module space, engineered substrate will continue to play a dominant role driven by 5G.

Regarding 5G <6 GHz, due to increase of frequency and bandwidth, silicon will be further push out by continuous improvement of those technologies SOI, GaAs, Piezo/POI technologies, GaN.

Regarding 5G mmWave, there are still open questions in the technologies battle field. Smartphone radiated power is limited to 23 dBm (EIRP) means 15 dBm per PA. CMOS bulk 28 nm products were launched on the market with limited PAE with questionable future if no major improvement. Both FD-SOI and RF-SOI are extremely well positioned in term of performance and cost trade off. Silicon Germanium (BiCMOS) is another alternative even looks less attractive for the moment. Regarding small cells, depending on the system approach (antenna array complexity), most technologies are in the technology field. In most cases, silicon and non silicon engineered substrates are the 5G mmWave most probable



technologies winner(s). Major 5G mmWave networks deployment and market traction is foreseen by 2023.



Figure 8-74 5G mmWave technologies battle field, source Analog Device – 5G mmWave IWPC white paper